

# Ion Beam Probe System for Potential Measurement in the Low Aspect-Ratio Torus Experiment Device

H. Tanaka<sup>1</sup>, S. Omi<sup>1</sup>, J. Katsuma<sup>1</sup>, M. Uchida<sup>1</sup>,  
T. Maekawa<sup>1</sup> and H. Iguchi<sup>2</sup>

<sup>1</sup> Graduate School of Energy Science, Kyoto University, Japan

<sup>2</sup> National Institute for Fusion Science, Toki, Japan

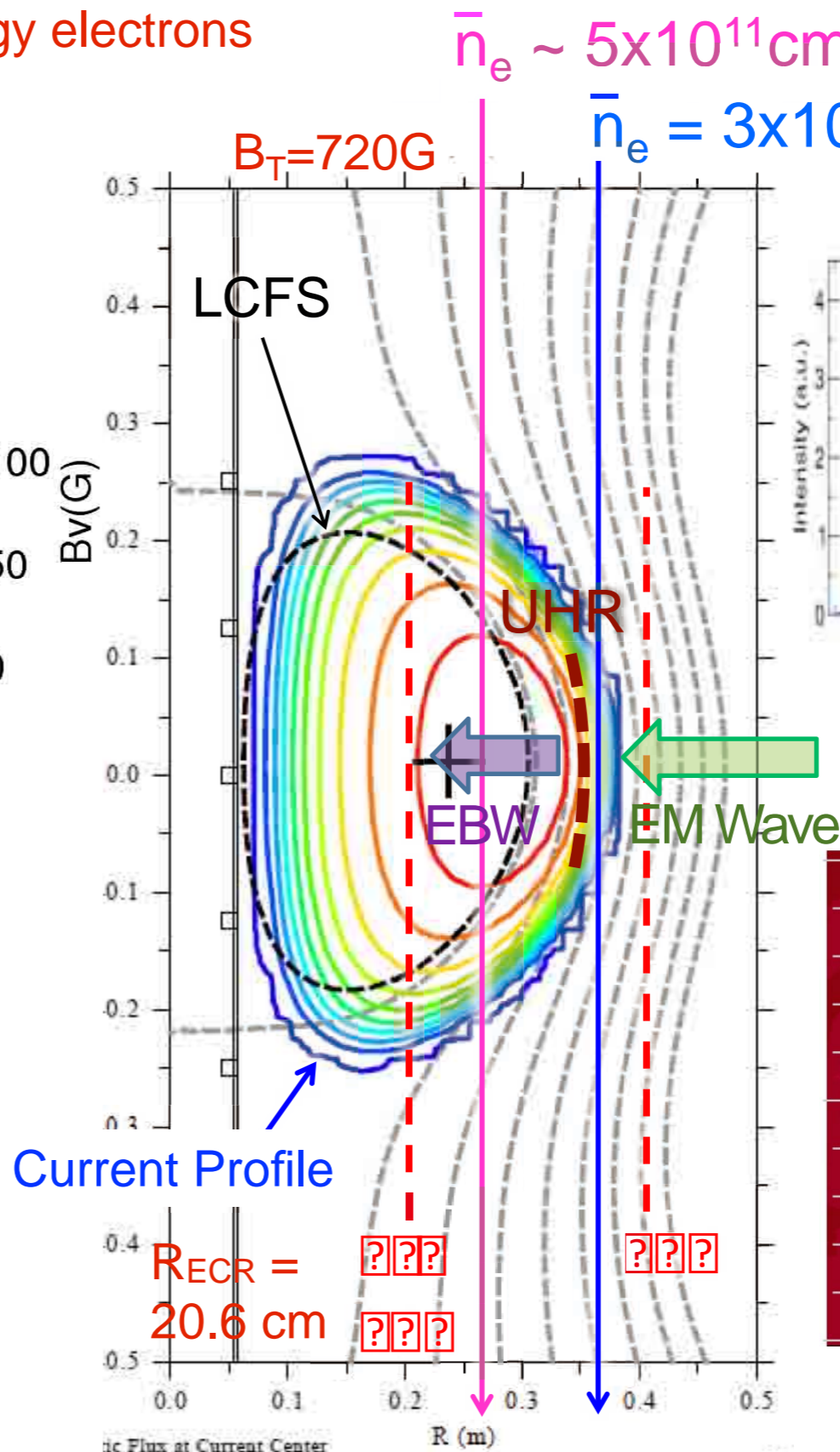
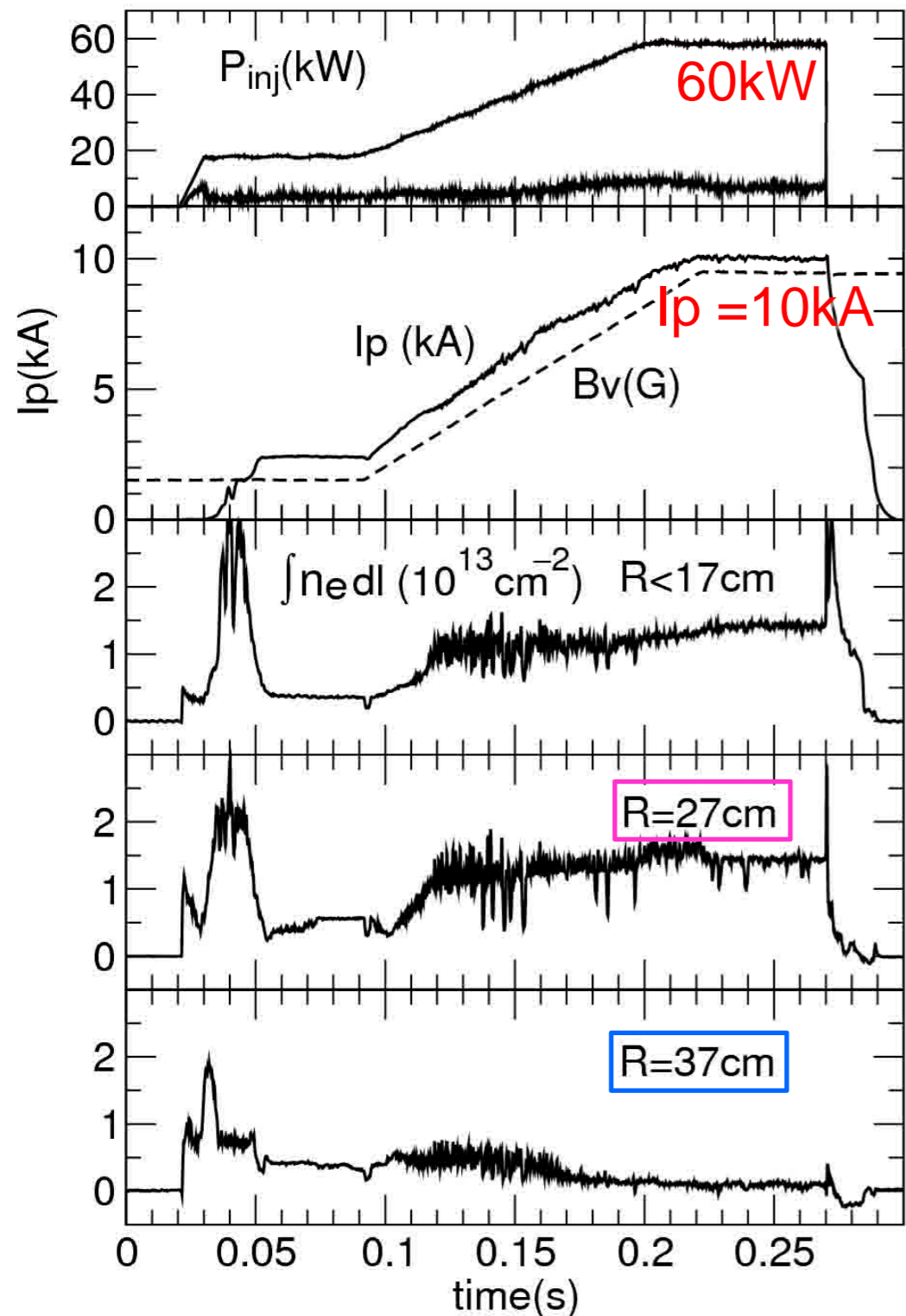
1. Background and Objectives
2. Overall System Configuration
3. Ion Source, Ion Gun
4. Estimation of the Secondary Ion Beam Current
5. Beam Control
  - Injection Beam Line
  - Collection Beam Line
  - Calculation Code for Ion Beam Orbit
6. Design of Energy Analyzer

# Microwave Spherical Tokamak

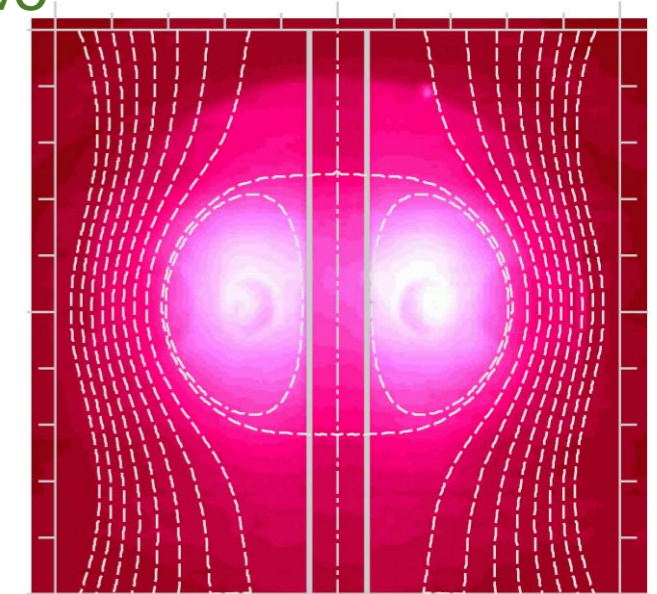
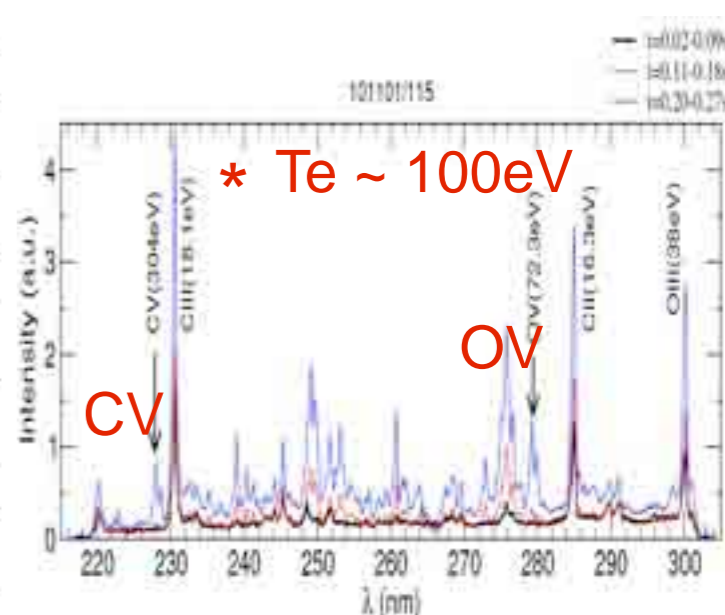
\* Overdense ( $n_e > 10 n_c$ ) plasma is maintained by EBW heating and current drive

\* Plasma current is carried by high energy electrons ( $\lesssim 100$  keV)

/A1/late20/101101/116/

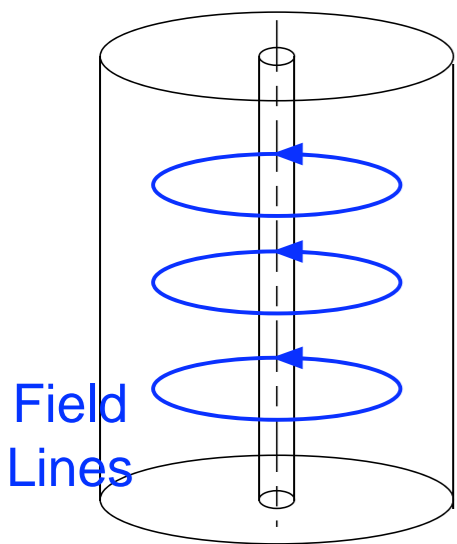


$\bar{n}_e \sim 5 \times 10^{11} \text{ cm}^{-3}$   $n_c = 7 \times 10^{10} \text{ cm}^{-3}$   
 $\bar{n}_e = 3 \times 10^{10} \text{ cm}^{-3}$

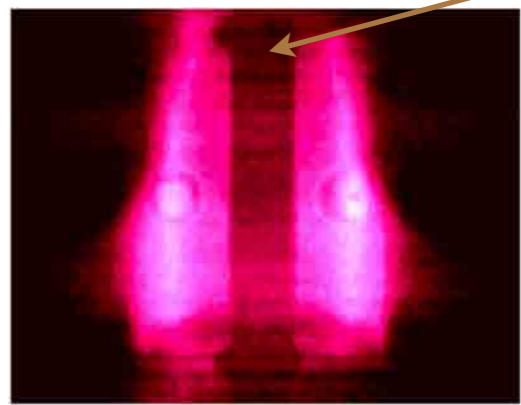


Visible Light Image

# Change of Potential Profile due to Bv

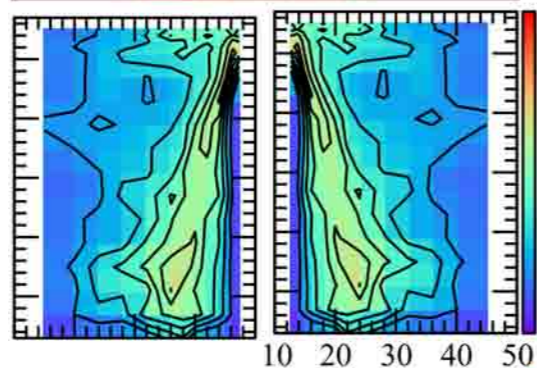


$B_v=0$

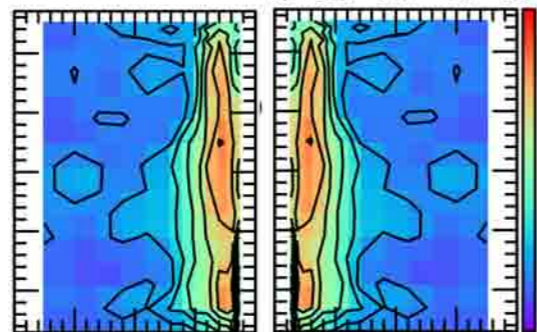


Center Pole

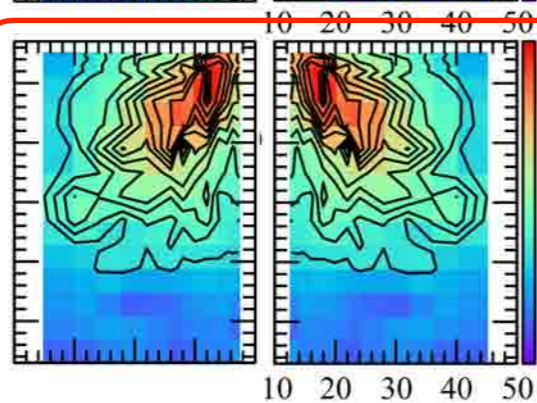
CCD Image



Electron Density  
 $n_e$

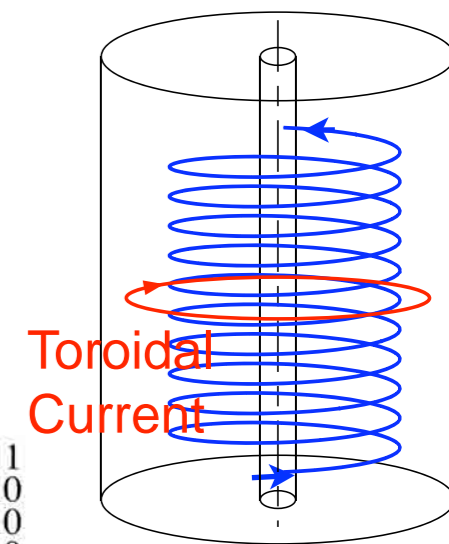
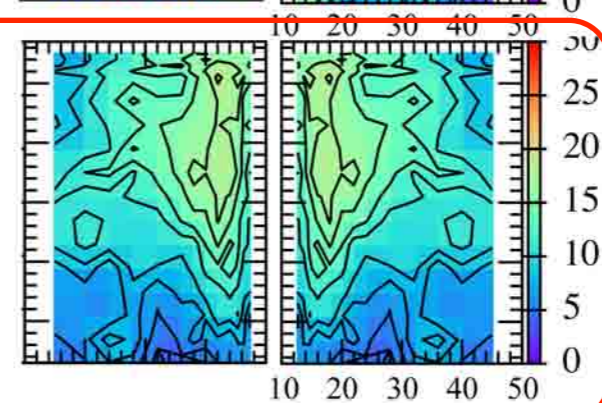
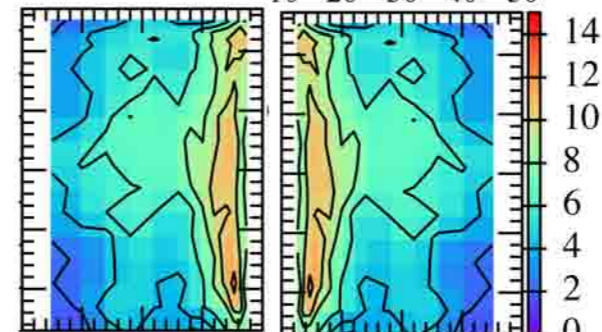
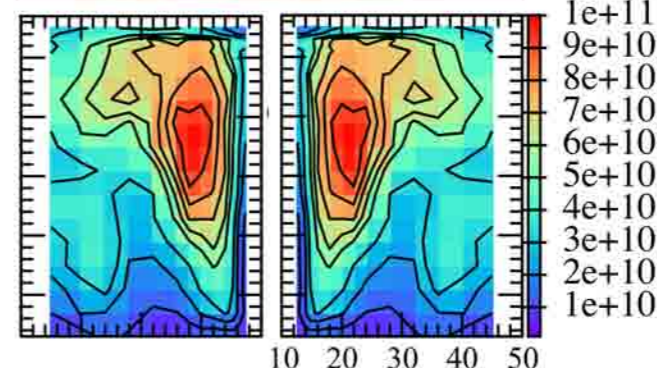
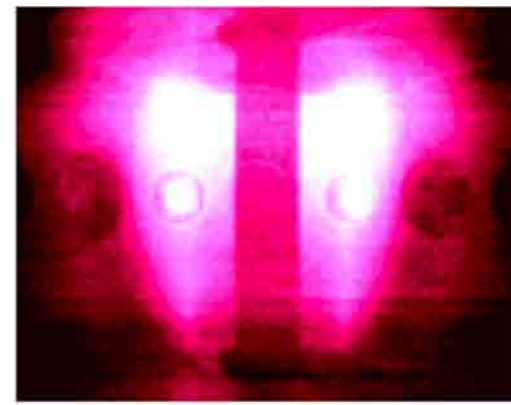


Electron Temperature  
 $T_e$

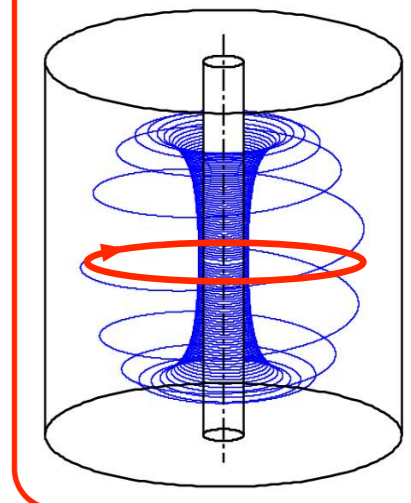


Space Potential  
 $V_s$

$B_v=6G$



Formation of initial closed flux surfaces



When the vertical field is applied, the space potential distribution changes to support the toroidal equilibrium.

## Microwave Spherical Tokamak

There is no measurement of potential distribution so far!

How the electric field has effects on

- ✓ Formation of initial closed flux surfaces
- ✓ Equilibrium and confinement

in the ST plasma produced and maintained by EBW/ECW heating and current drive ?

- \* Measurement of electrostatic potential distribution
- \* Electron temperature measurement ( $10 < T_e < 100$  eV)
- \* Plasma current profile measurement with aid of magnetic measurement
- \* Measurement of density fluctuation
- \* Measurement of potential and magnetic field fluctuation

# Overall System Configuration

## Target Plasma Parameters

$B_t = 480\text{G}, 720\text{G}$   
@  $R=25\text{cm}$

$R_{\text{ECR}} = 13.7\text{cm}, 20.6\text{cm}$   
for  $2.45\text{GHz}$

$B_v = 15 \sim 100\text{G}$   
 $I_p \lesssim 10\text{kA}$

Core

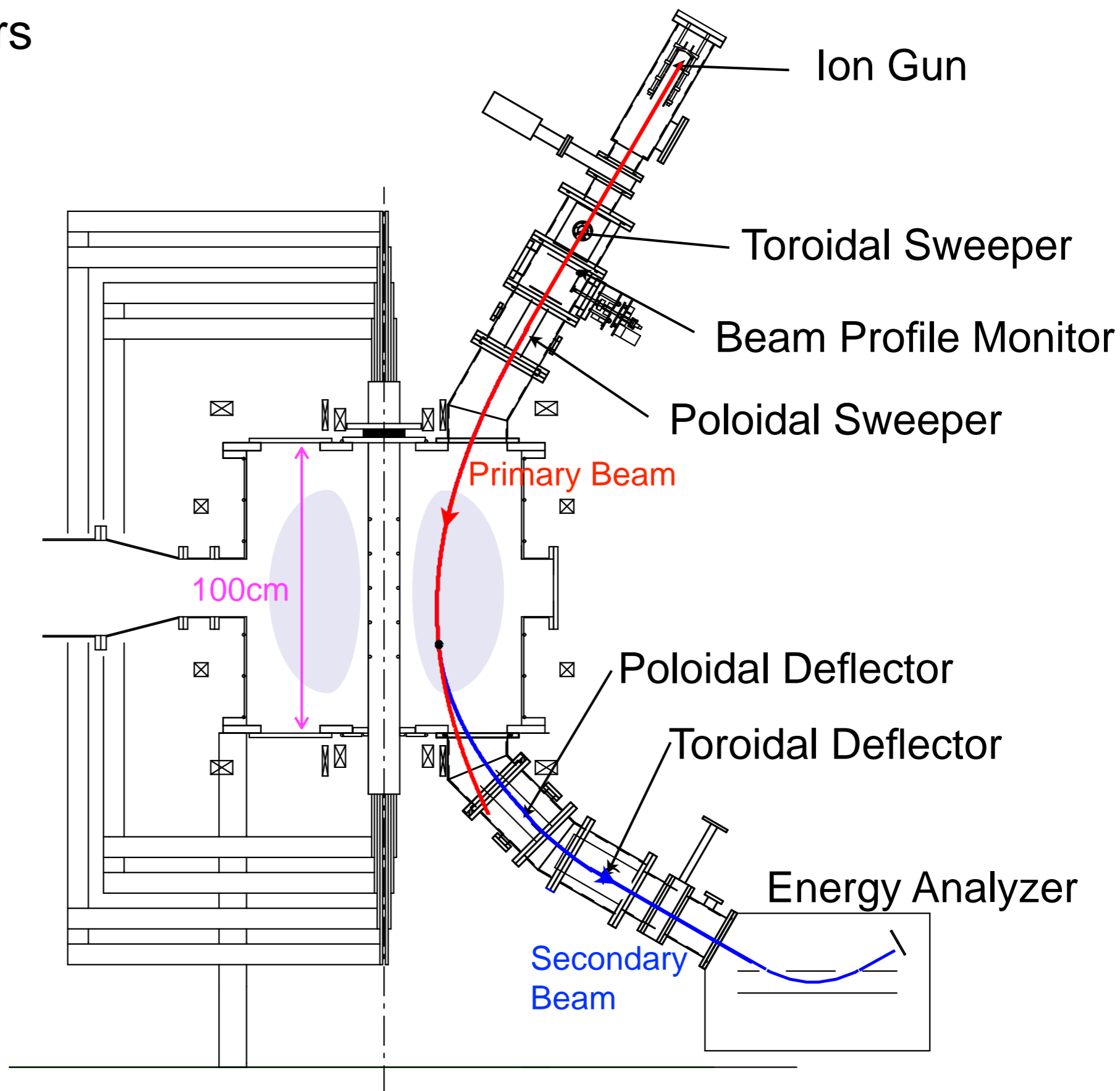
$10^{11} \sim 10^{12} \text{ cm}^{-3}$

$\sim 100 \text{ eV}$

Peripheral

$10^9 \sim 10^{10} \text{ cm}^{-3}$

$10 \sim 50 \text{ eV}$



# Ion Source & Ion Gun

## Ion Source

$\text{Li}^+$ ,  $\text{Na}^+$ ,  $\text{K}^+$ ,  $\text{Rb}^+$ ,  $\text{Ce}^+$

Thermionic ion source ... low energy spread ( $< 1\text{eV}$ )

Na zeolite base

Exchange Na ions with alkali metal (Li, K, Rb, Ce) ions in hot water solution

Recrystallization at  $\sim 1000^\circ\text{C}$  in vacuum

6mm  
↔



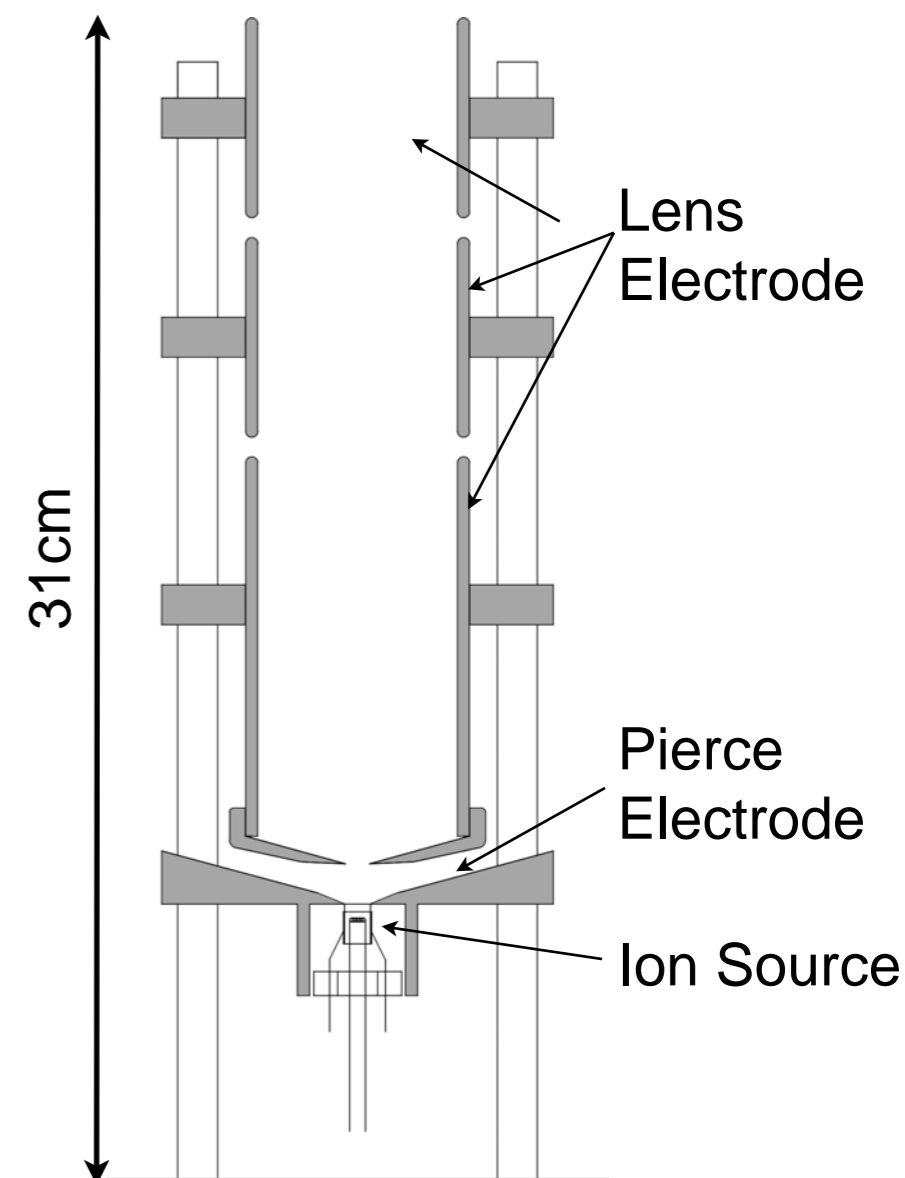
## Ion Gun

Gun Voltage  $V_G \leq 20\text{kV}$

Pierce electrode

3 Cylindrical lens electrode

The same type used for HIBP system of CHS





# Estimation of Secondary Beam Current

Primary Beam Current

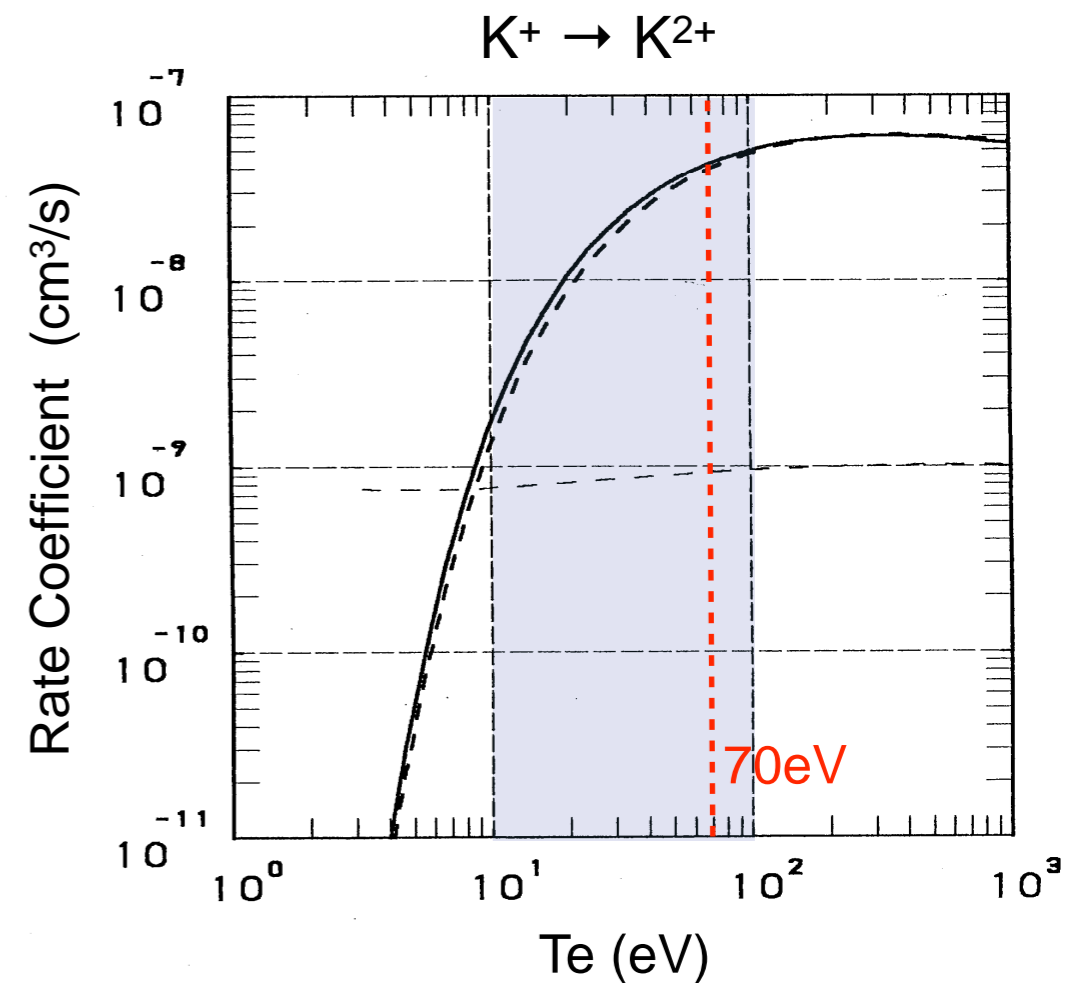
$$I_p = n_b e v_b A$$

Secondary Beam Current

$$I_s = Z_i e n_b n_e \langle \sigma v \rangle_i A l$$

Ratio

$$\frac{I_s}{I_p} = Z_i n_e l \frac{\langle \sigma v \rangle_i}{v_b}$$



$A^+ \rightarrow A^{2+}$

ions	mass number	Ionization Energy	$\langle \sigma v \rangle_i @ Te=70eV$
Li <sup>+</sup>	7	75.6 eV	$0.1 \times 10^{-8} \text{ cm}^3/\text{s}$
Na <sup>+</sup>	23	47.3 eV	$0.9 \times 10^{-8} \text{ cm}^3/\text{s}$
K <sup>+</sup>	39	31.6 eV	$4 \times 10^{-8} \text{ cm}^3/\text{s}$
Rb <sup>+</sup>	85	27.3 eV	$\sim 8 \times 10^{-8} \text{ cm}^3/\text{s}$
Cs <sup>+</sup>	133	23.2 eV	$\sim 10 \times 10^{-8} \text{ cm}^3/\text{s}$

Secondary Beam Current

1.4 nA

22 nA

130 nA

380 nA

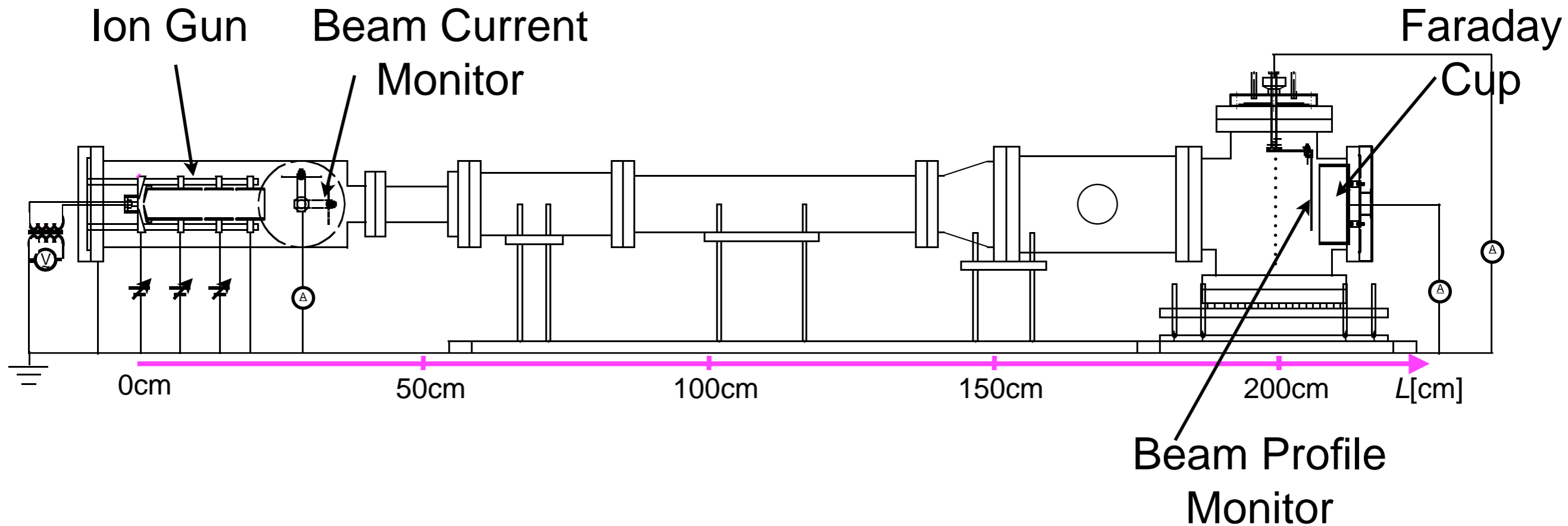
590 nA

$Z_i = 2$   
Length of Sample Volume  
 $l = 1 \text{ cm}$

Primary Beam Energy  
20 keV, Current  $100 \mu\text{A}$   
 $n_e = 5 \times 10^{11} \text{ cm}^{-3}$   
 $T_e = 70 \text{ eV}$

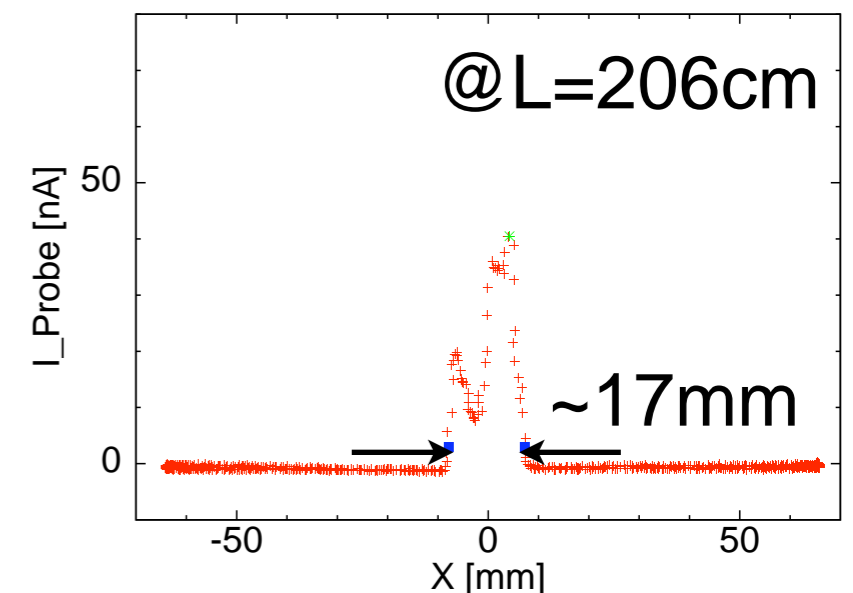


# Test of Ion Gun at Test Bench

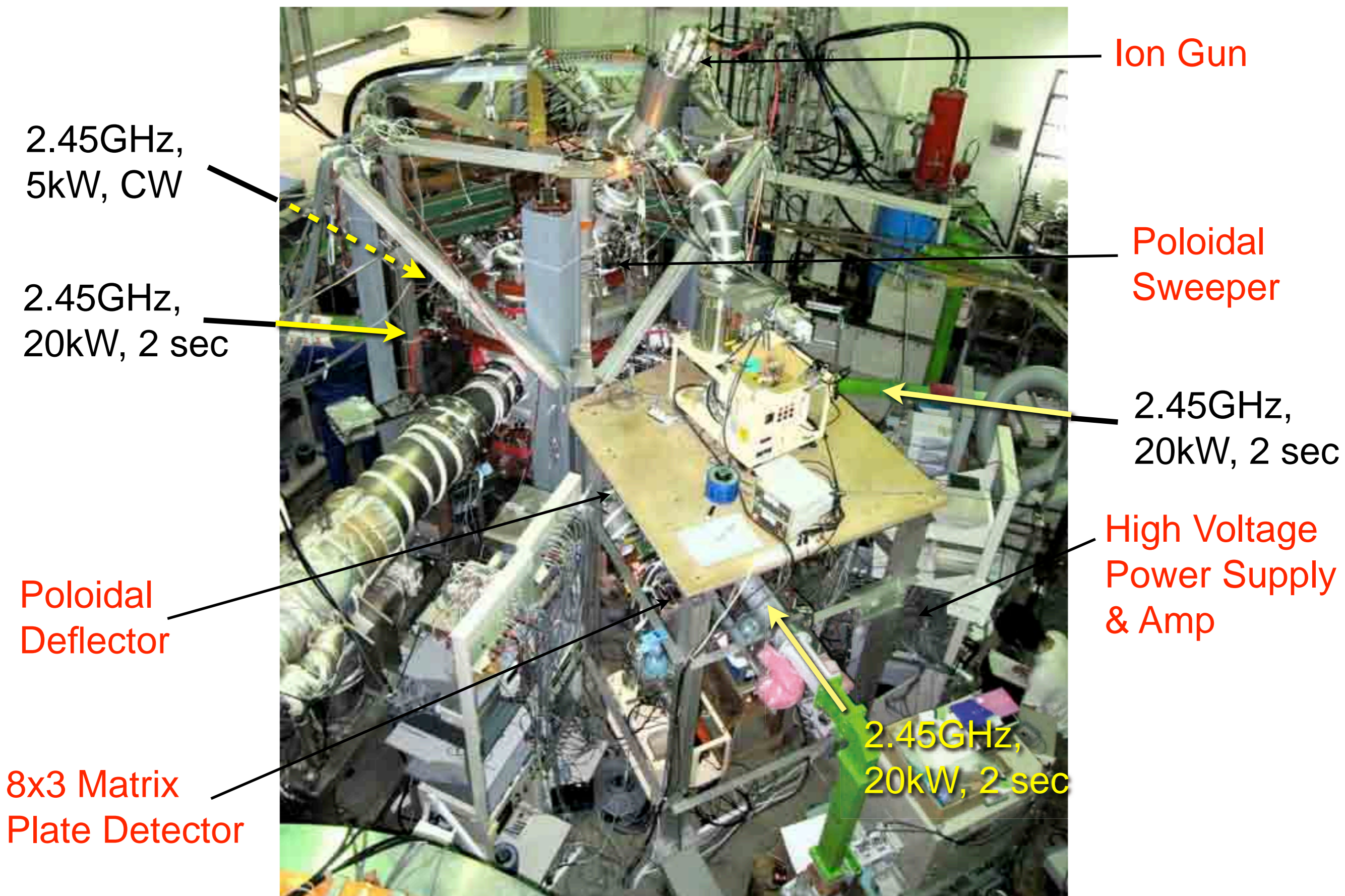


- \*  $K^+$  ion current more than  $100 \mu A$  is obtained sometimes.
- \*  $K^+$  ion current of  $\sim 40 \mu A$  is routinely extracted.
- \* Beam diameter is less than 2 cm at 206 cm away from the ion source (corresponding to  $z \sim 10$  cm in LATE)

$K^+$ , 18keV



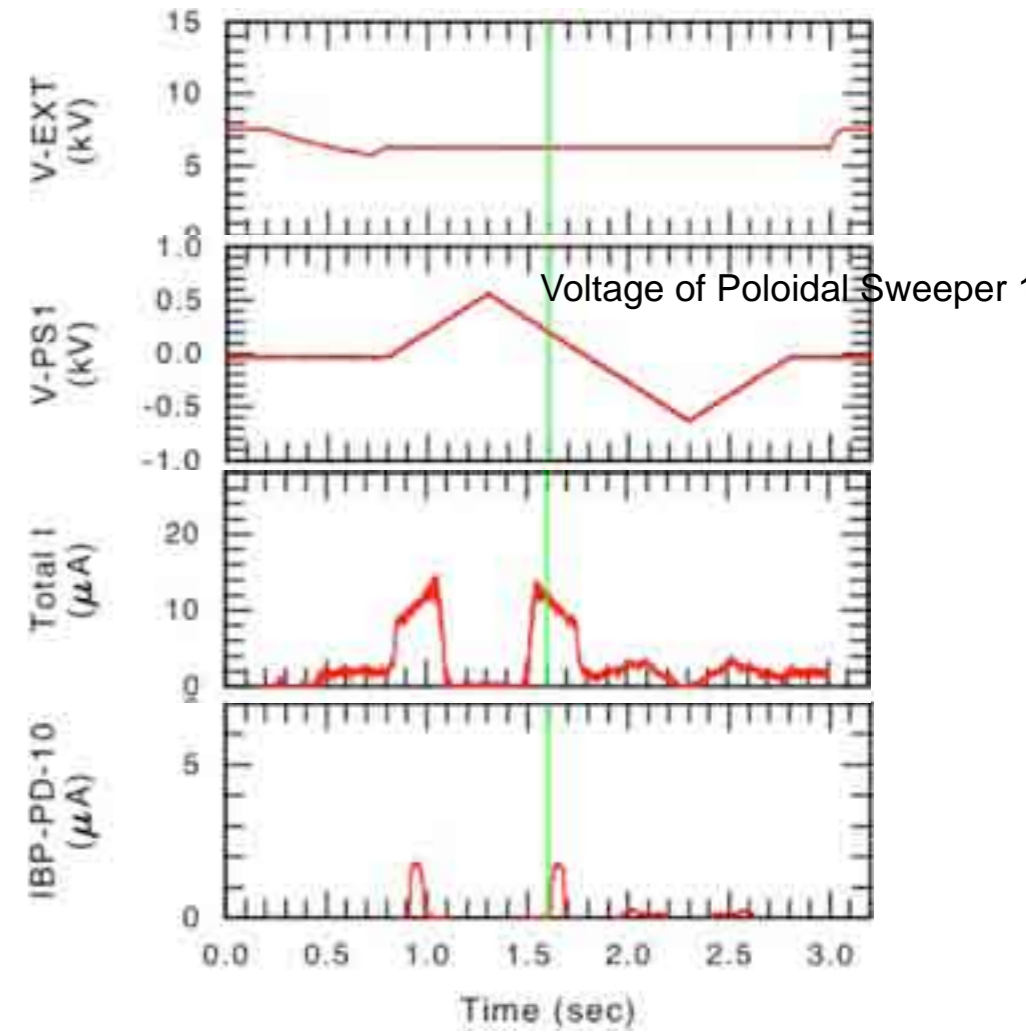
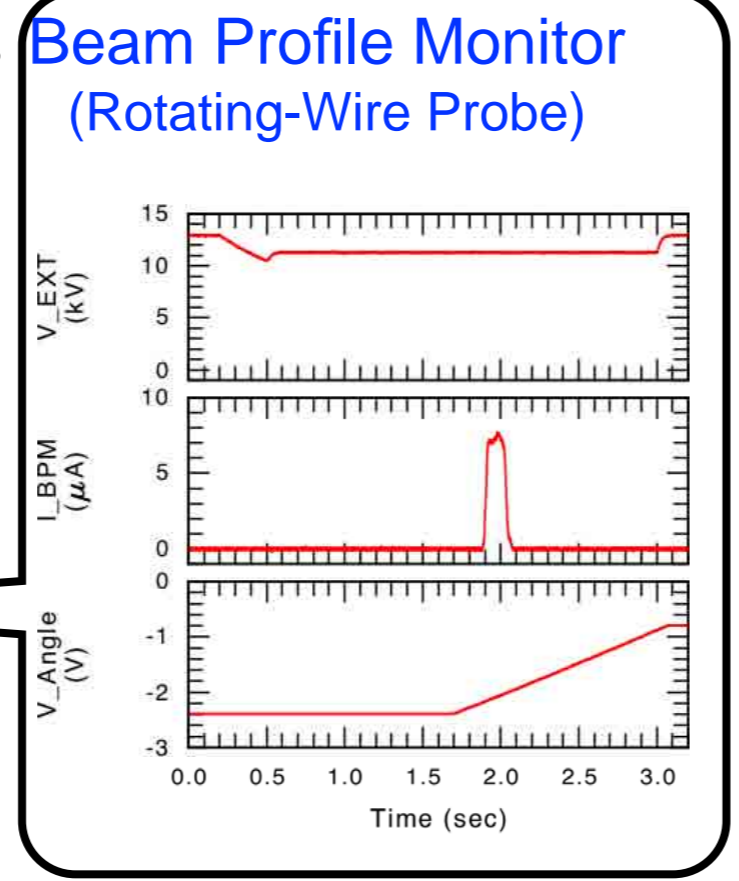
# Installation of IBP Beam Line to LATE



# Test of Beam Injection (1)

$K^+$ , 8~14keV  
 $B_t = 480G$

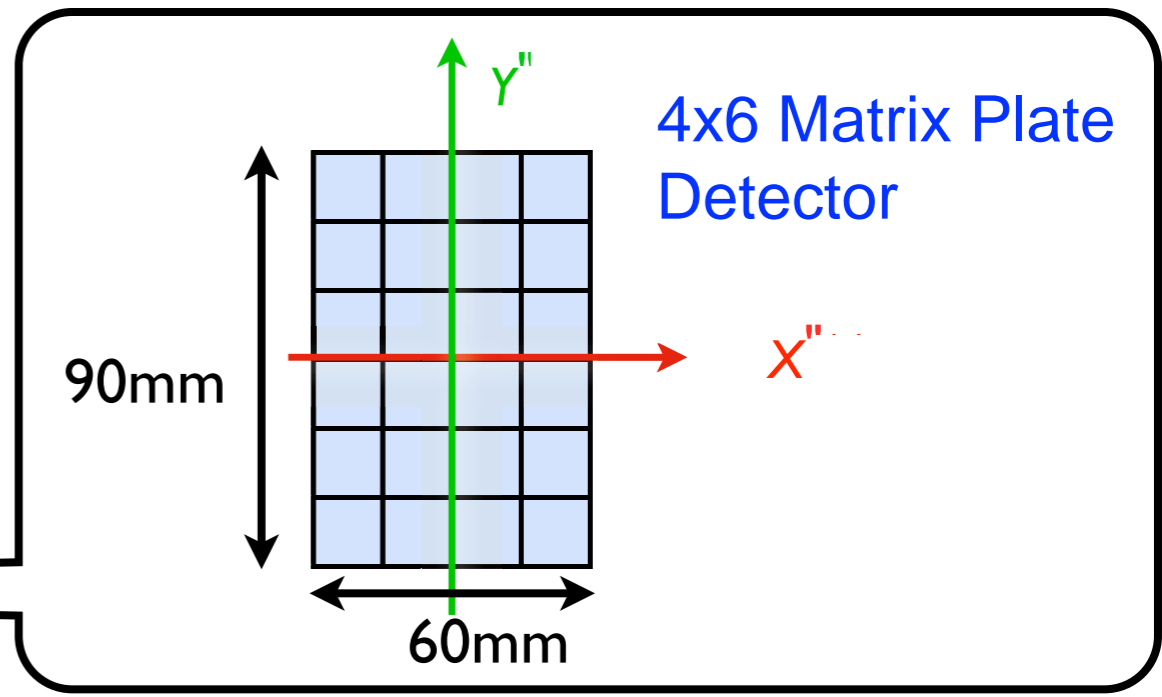
Ion Gun



Toroidal Sweeper

Poloidal Sweeper

**Linearly Movable Detector (5+6 two-lined plates)**



# Test of Beam Injection (1)

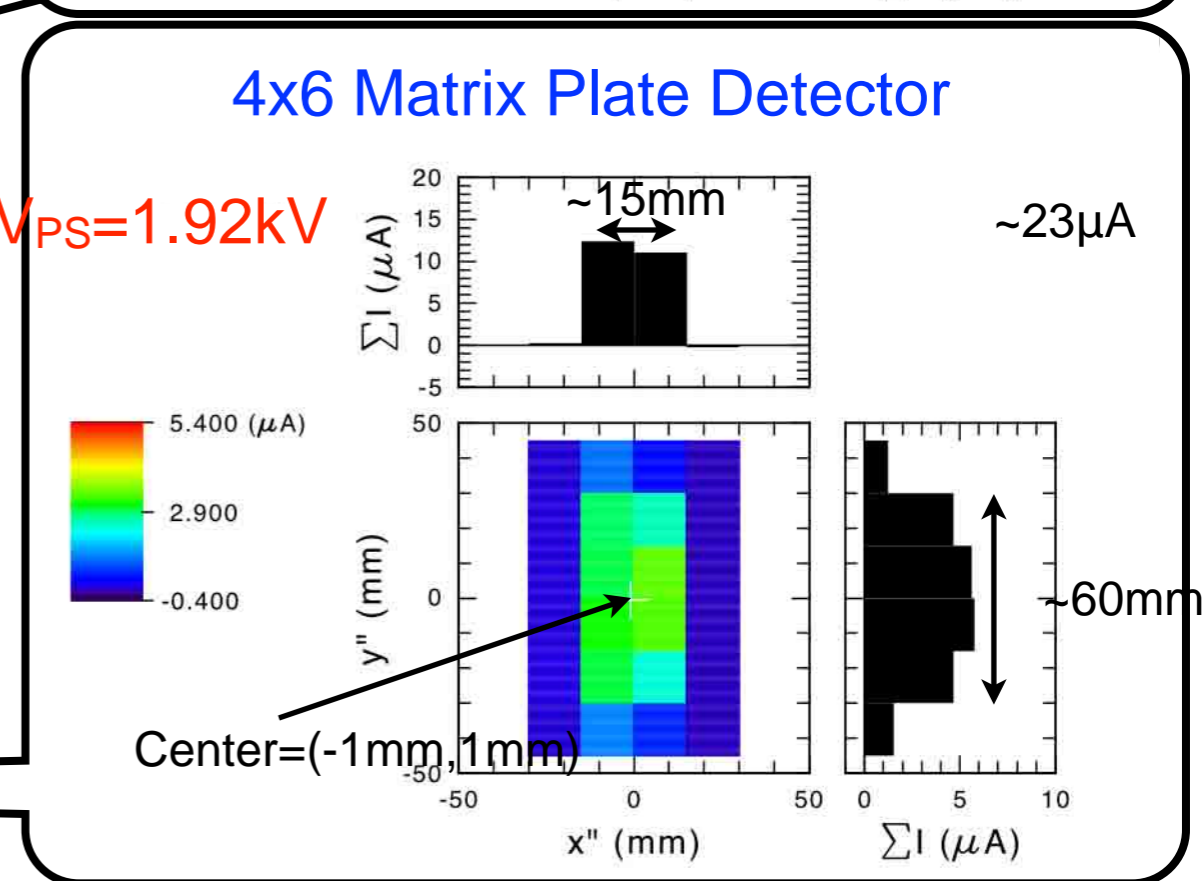
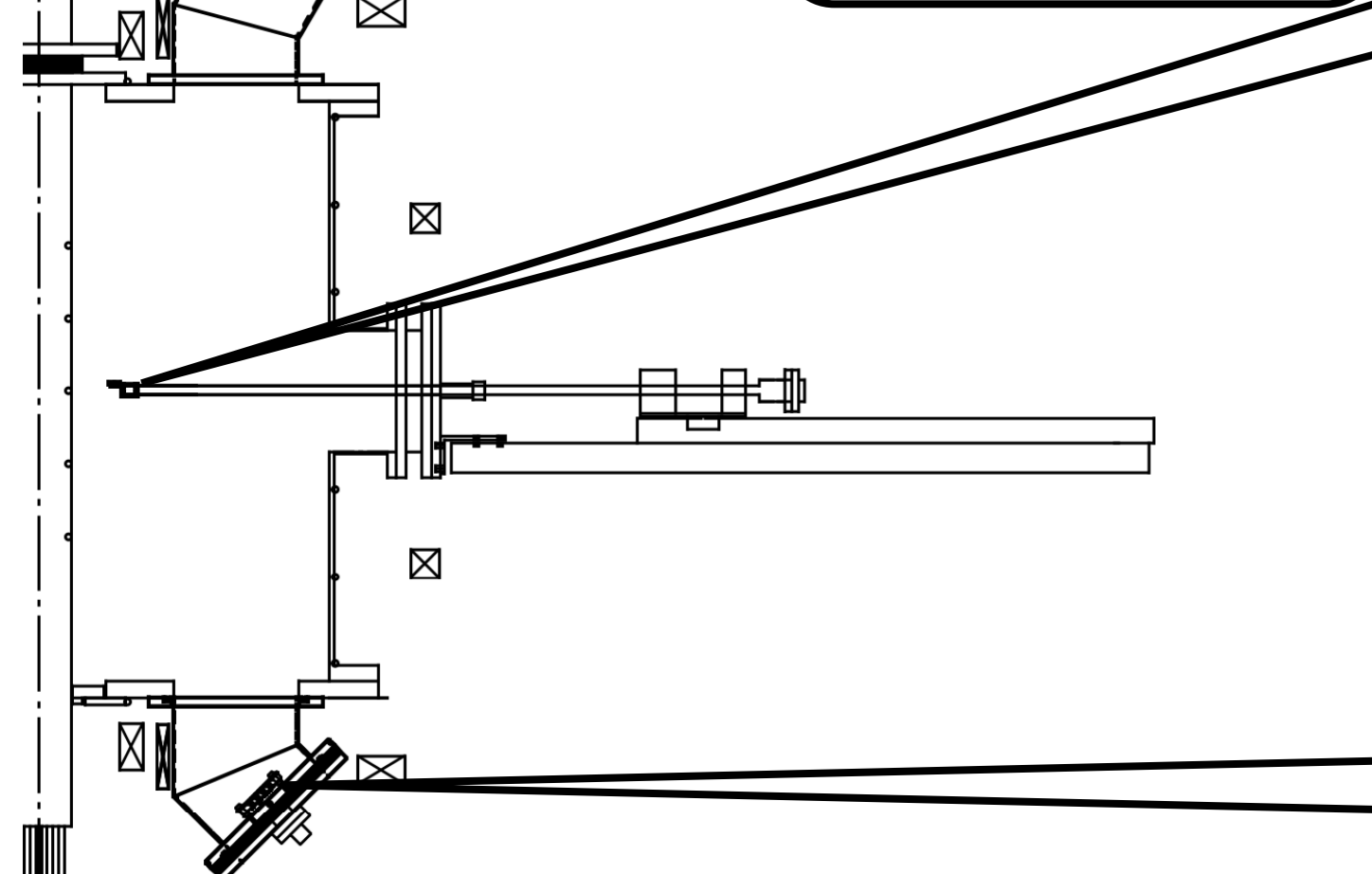
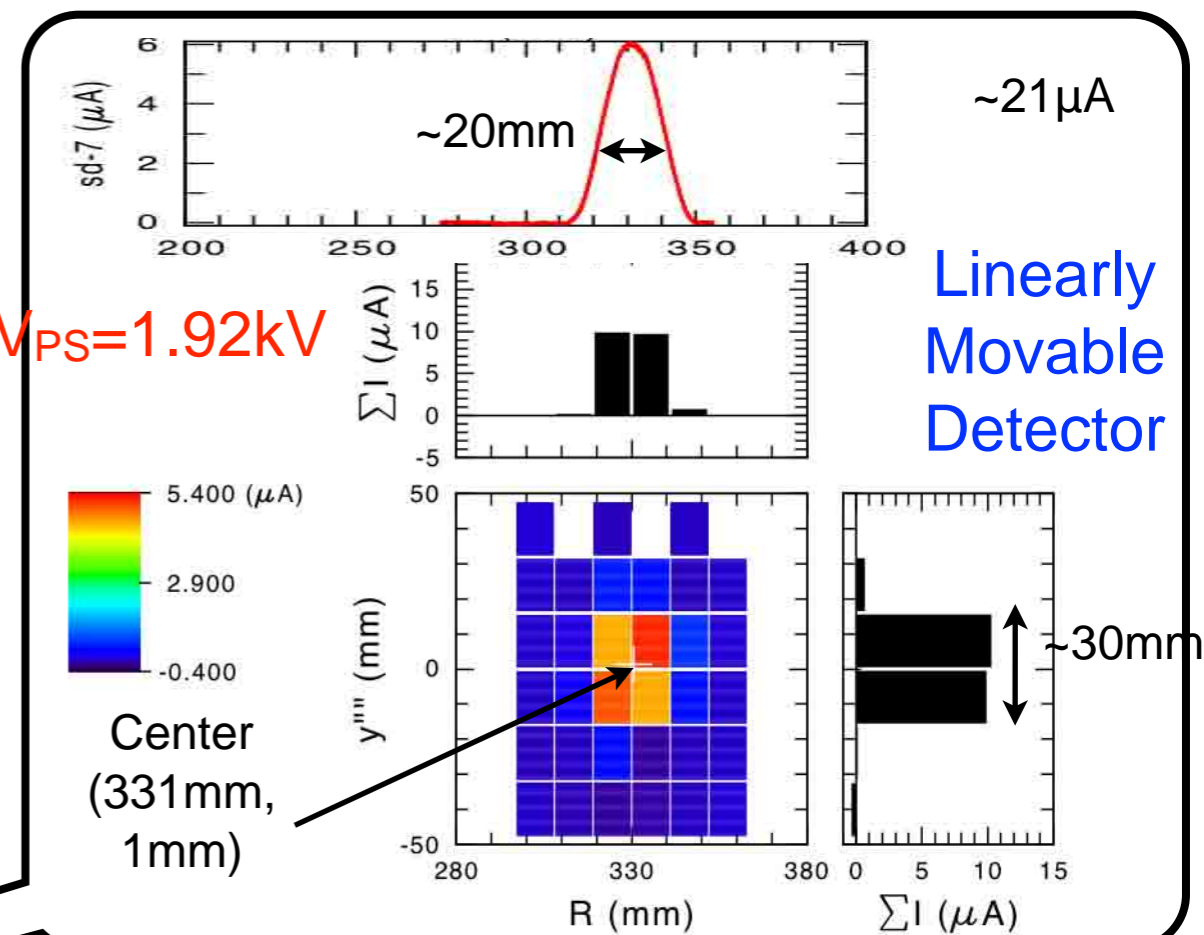
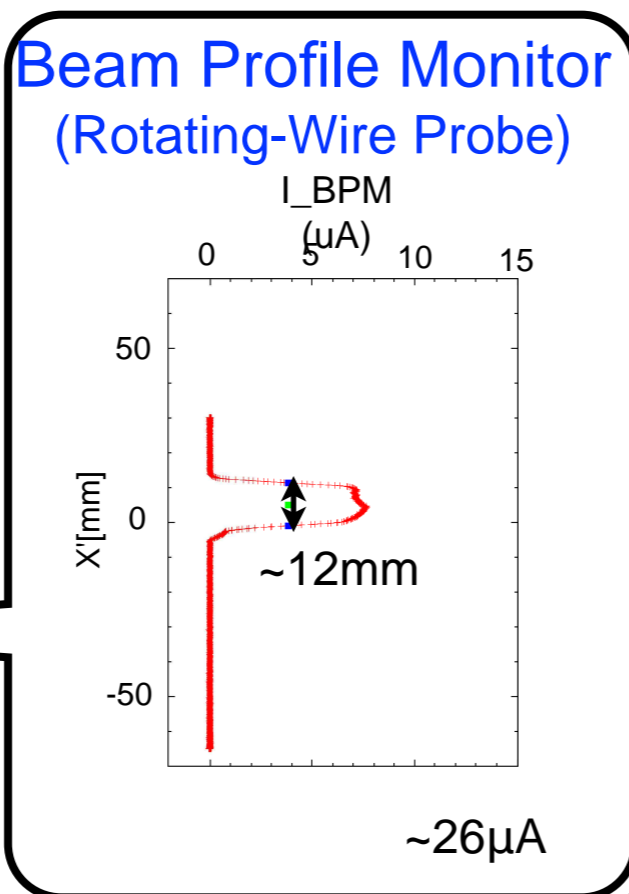
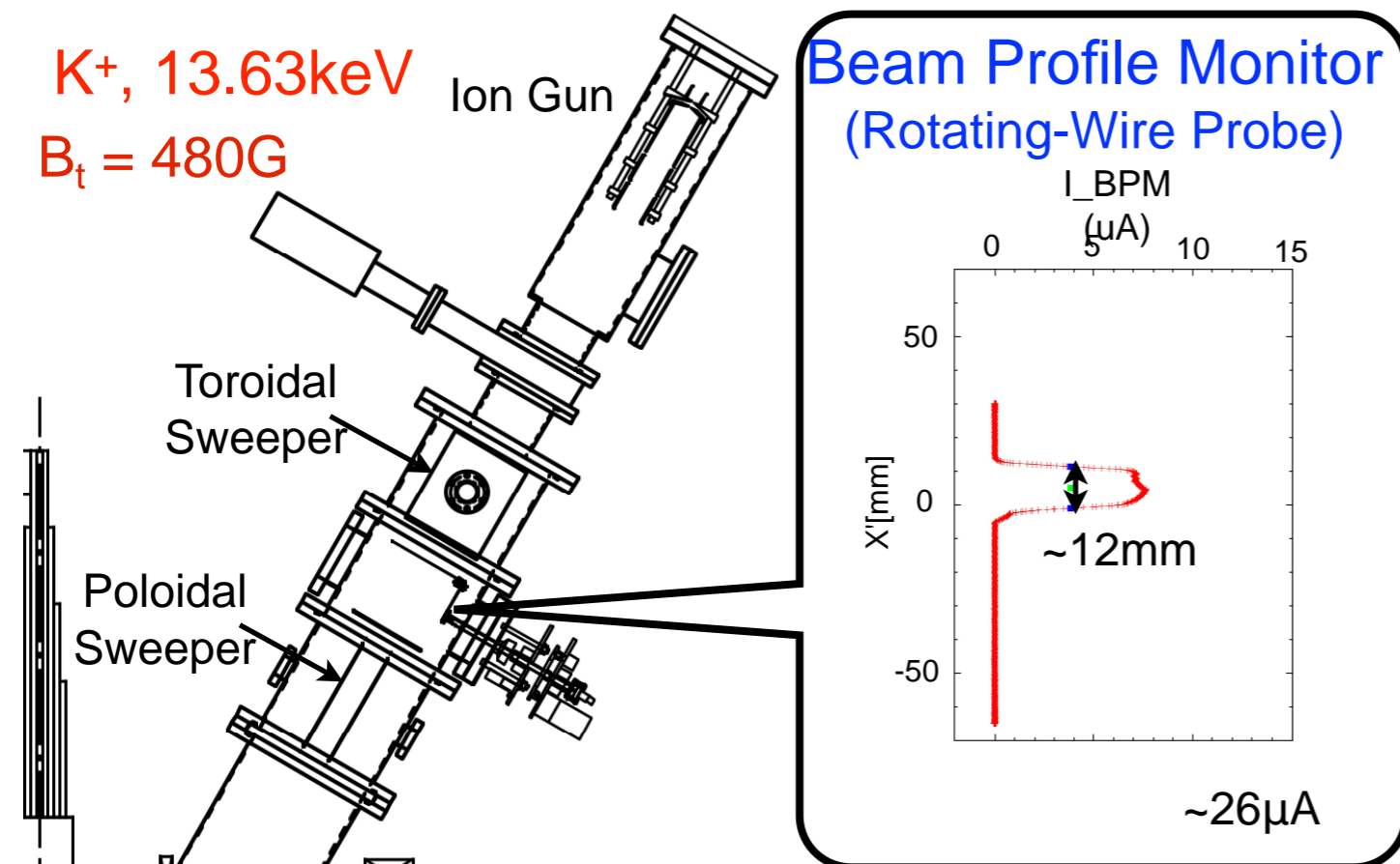
$K^+$ , 13.63keV  
 $B_t = 480G$

Ion Gun

Beam Profile Monitor  
 (Rotating-Wire Probe)

$V_{PS} = 1.92kV$

Linearly  
 Movable  
 Detector





# Comparison of Measured Position and Calculated One (1)

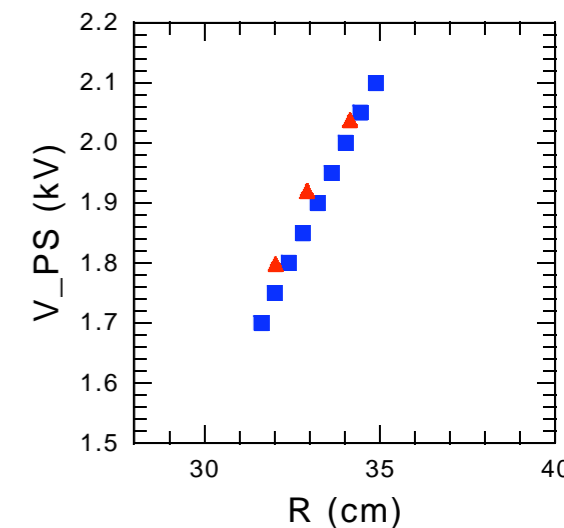
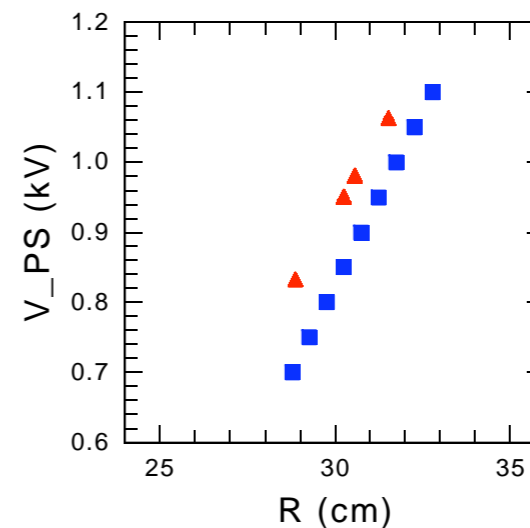
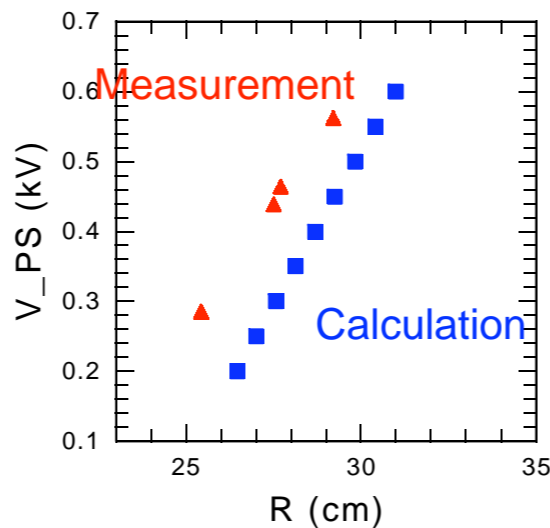
$K^+$   $B_t = 480G$

8.08keV

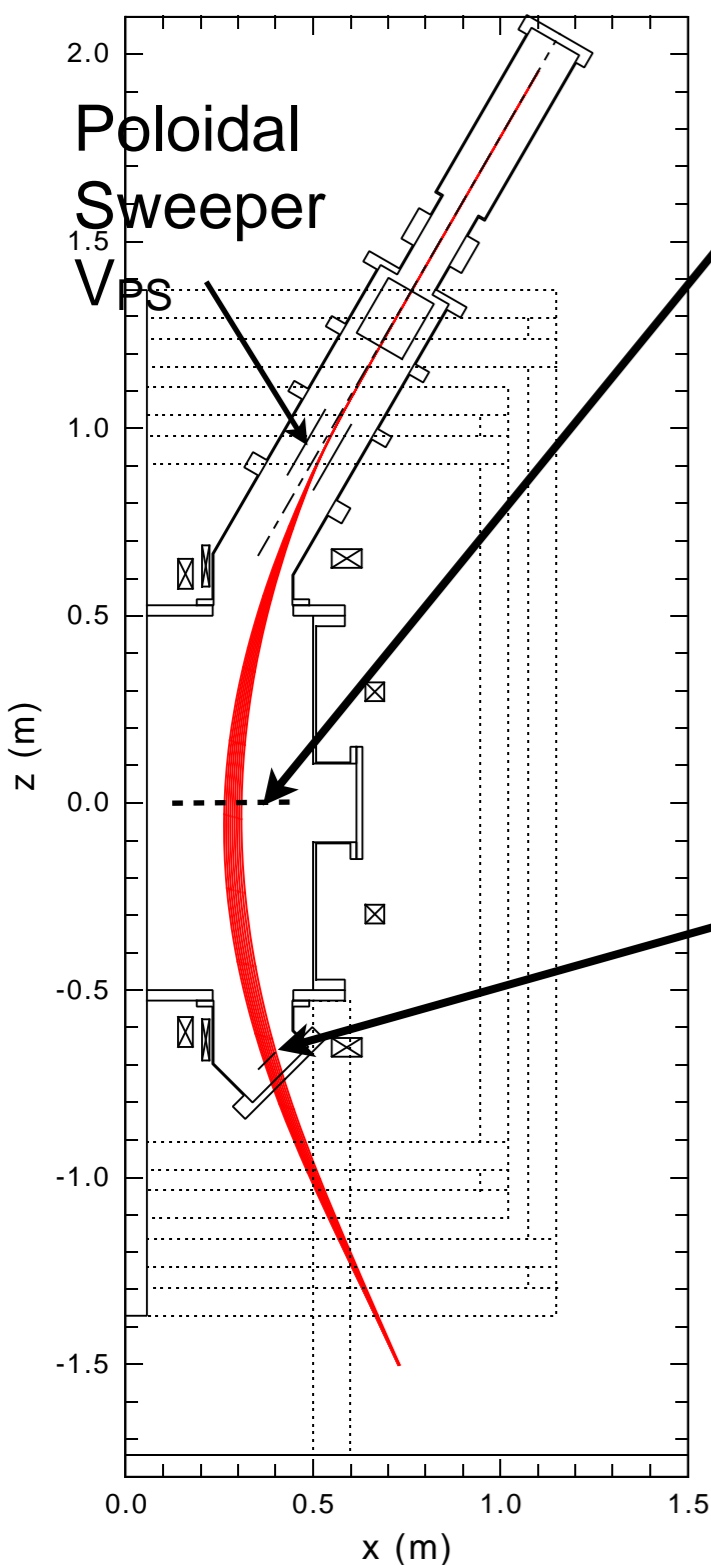
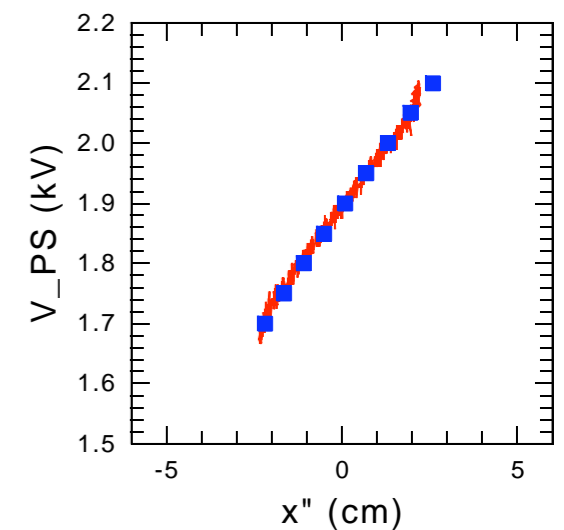
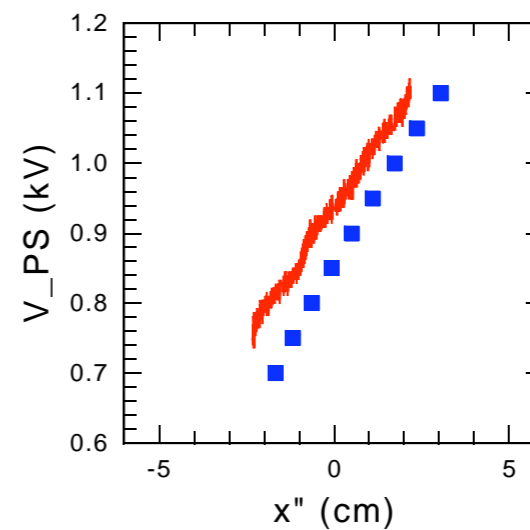
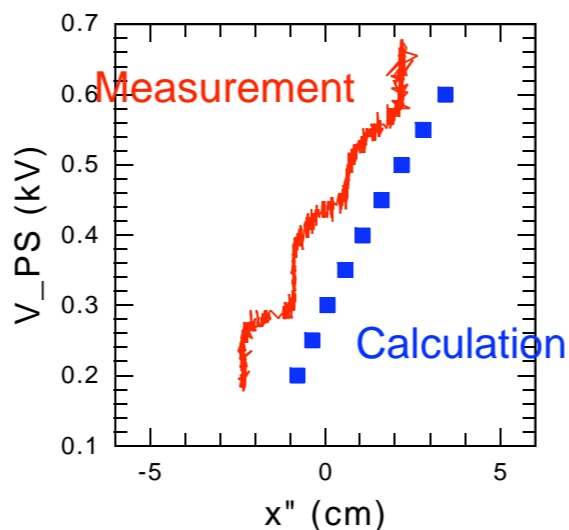
9.91keV

13.63keV

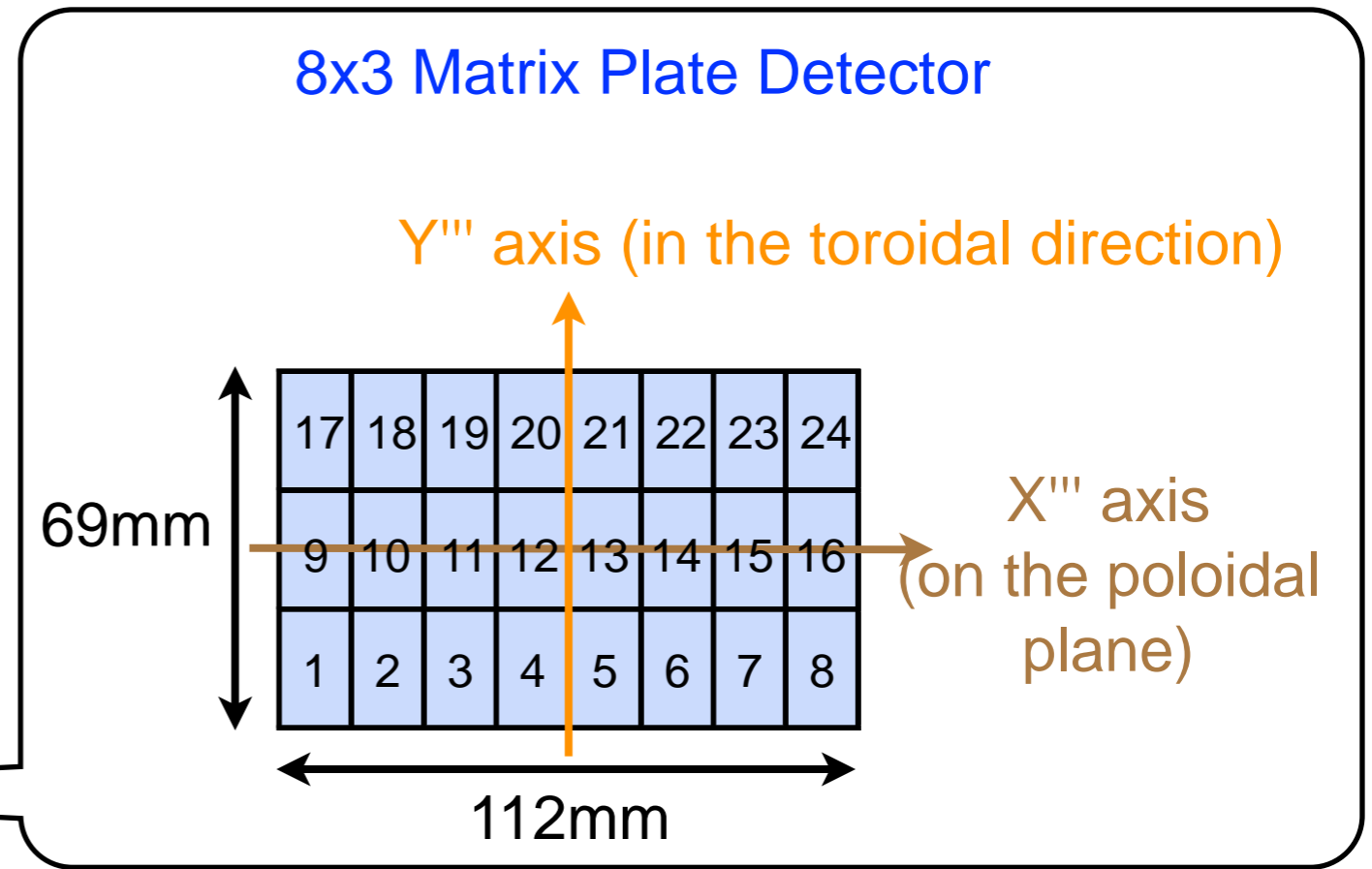
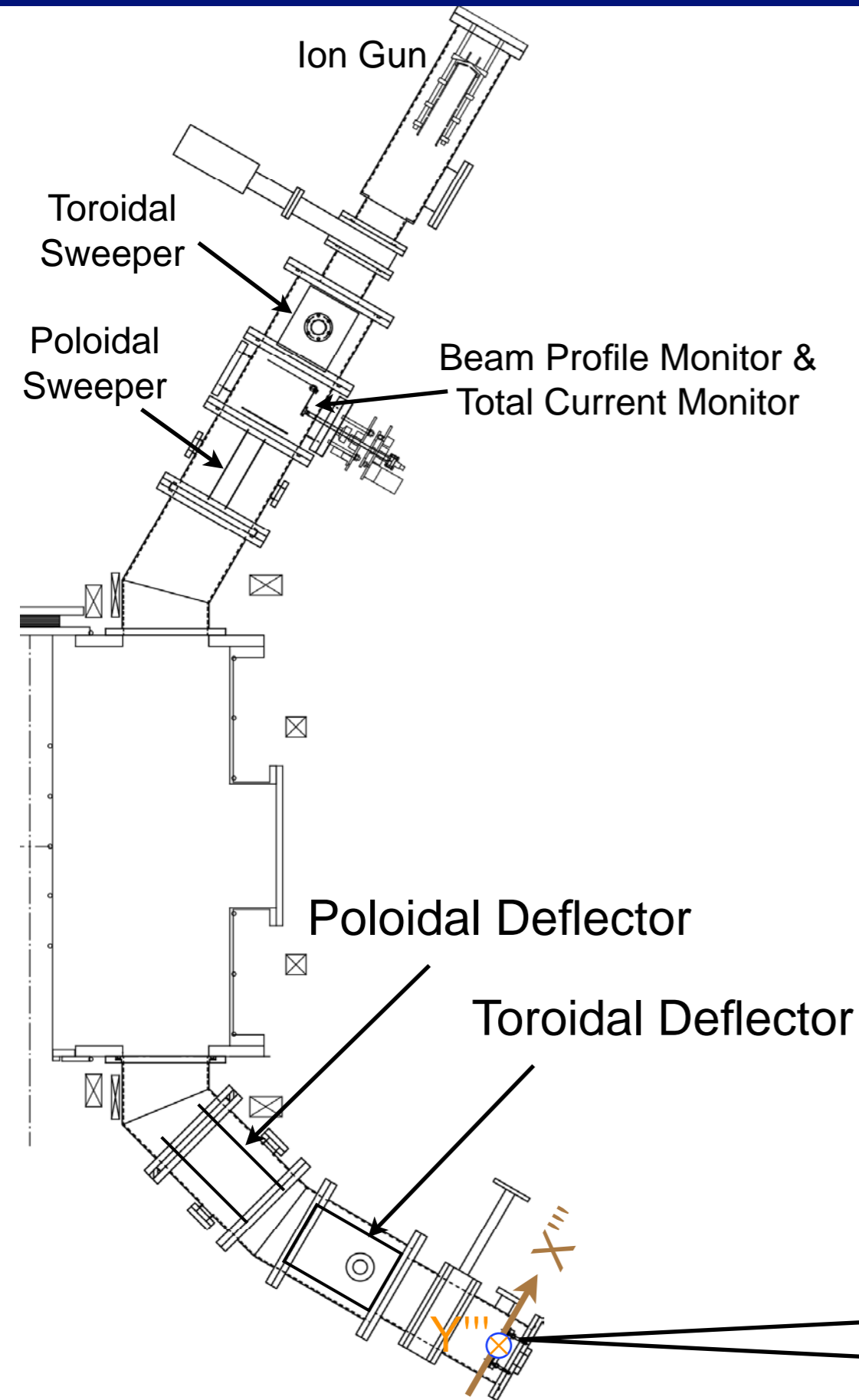
$z=1.5cm$  (Movable Detector)



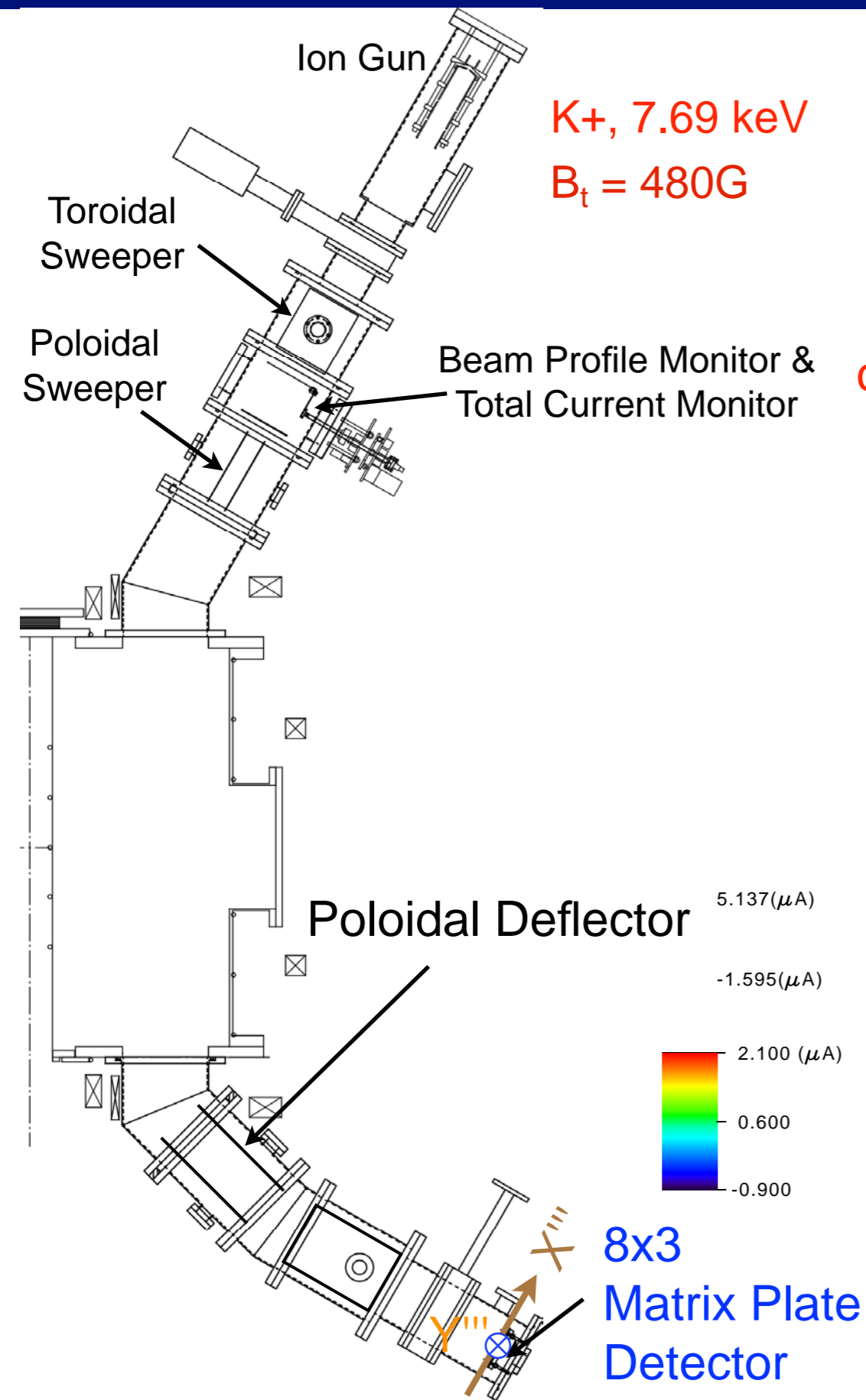
Bottom Port (4x6 Matrix Plate Detector)



# Test of Beam Injection (2)



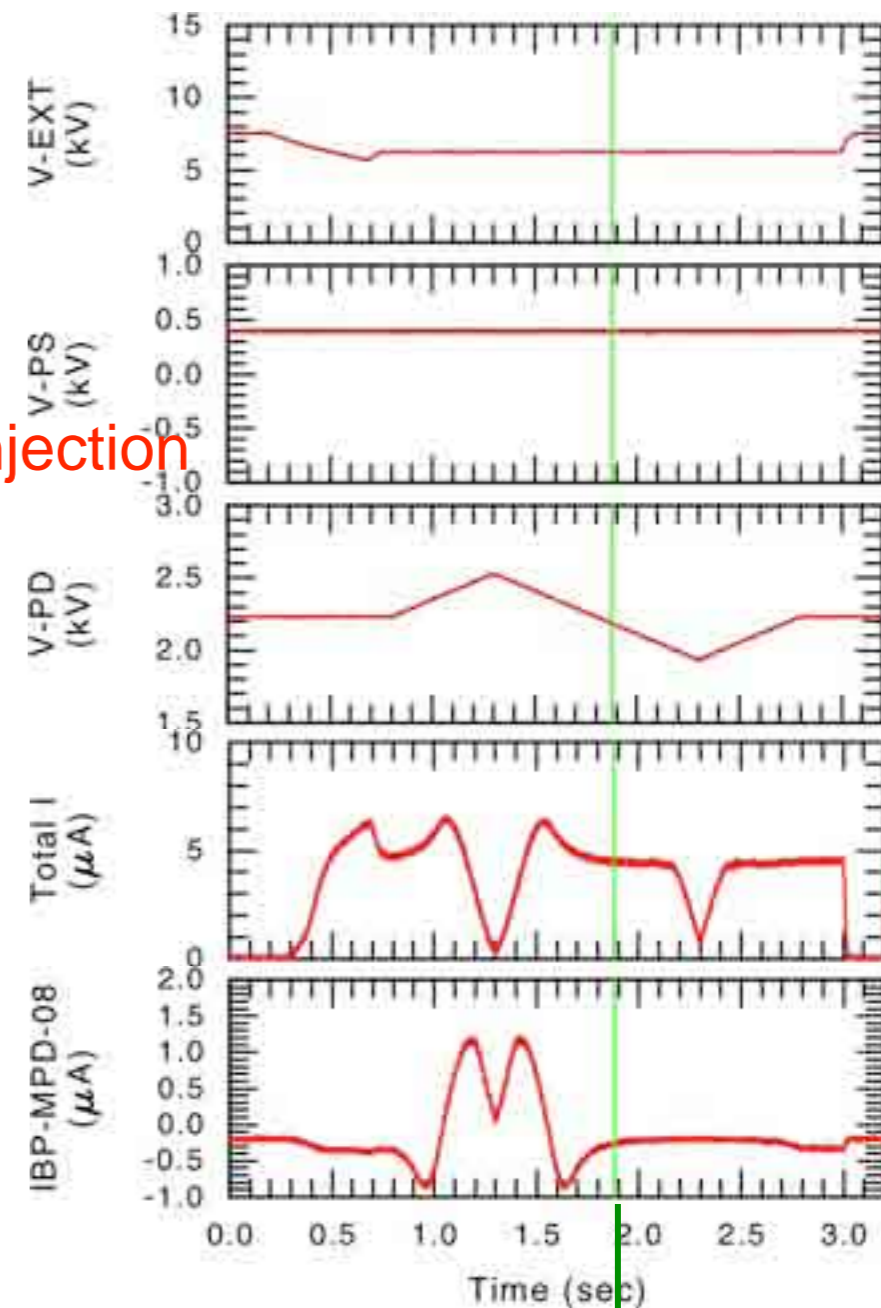
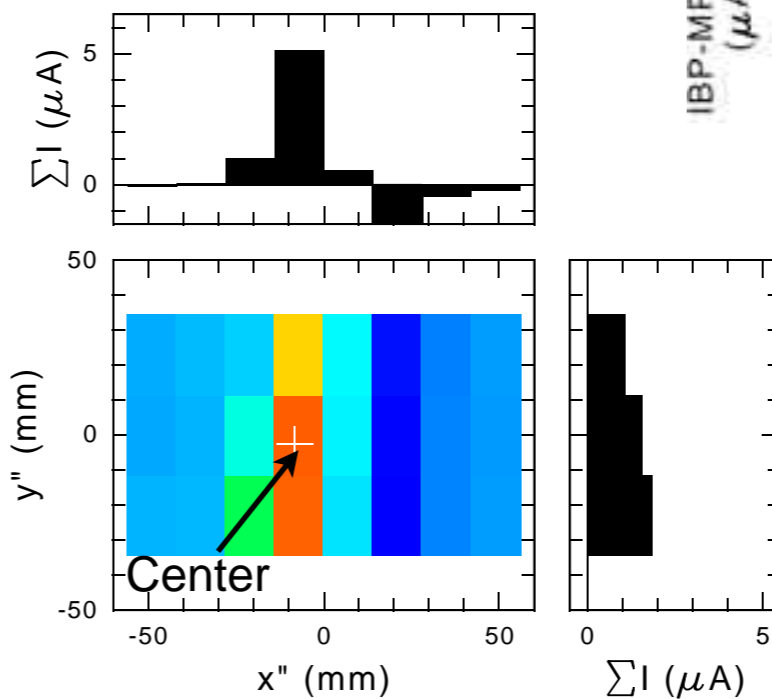
# Test of Beam Injection (2)



$K^+$ , 7.69 keV  
 $B_t = 480G$

$V_{PS} = 0.4$  kV  
 constant during beam injection

$V_{PD} = 1.8 \sim 2.6$  kV



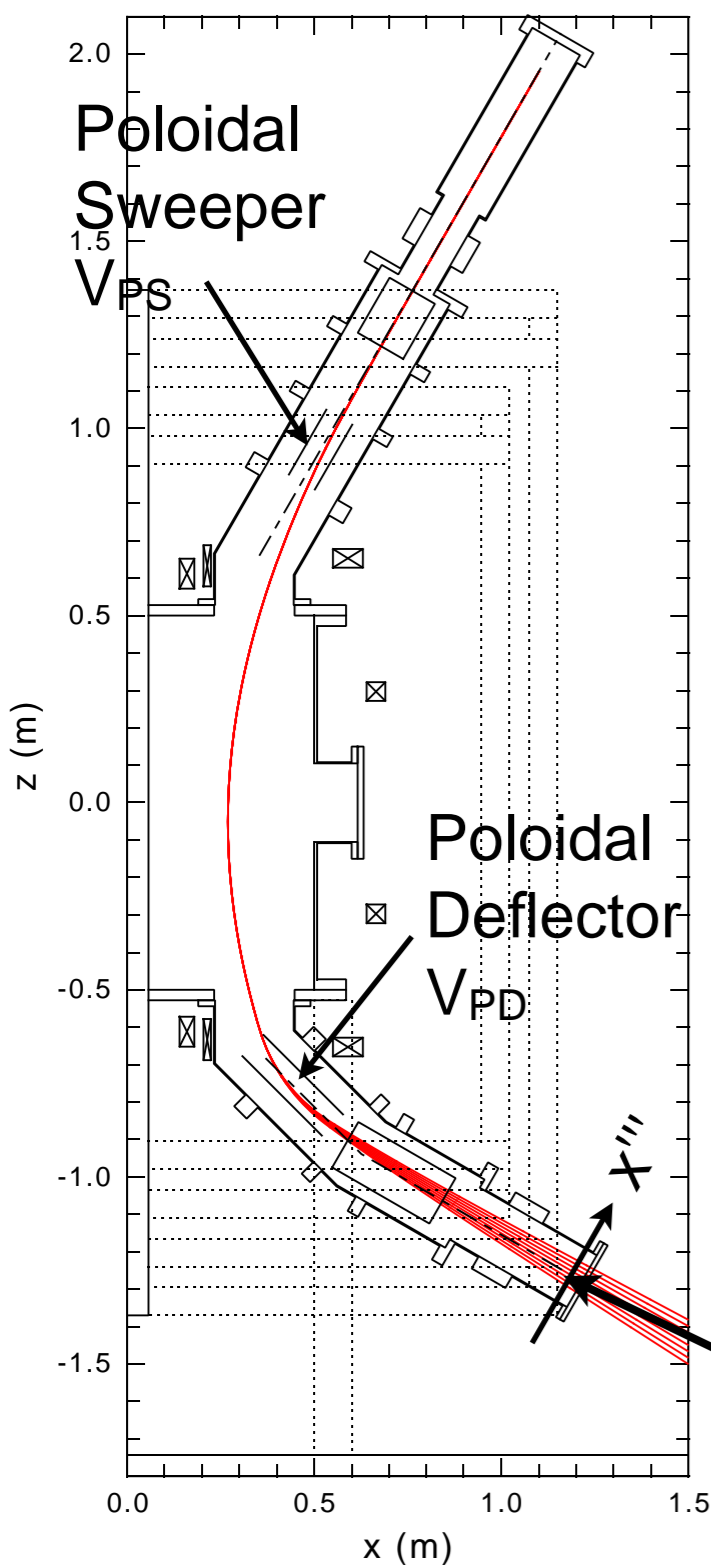
$t = 1.88$  sec

$V_{PD} = 2.18$  kV



# Comparison of Measured Position and Calculated One (2)

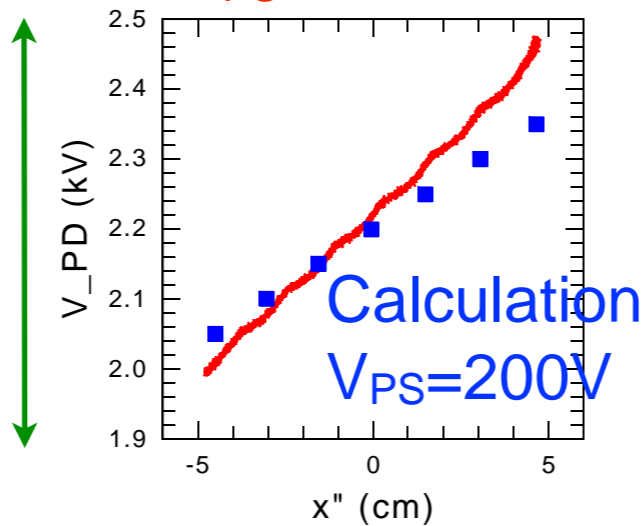
$K^+$   $B_t = 480G$



\*  $V_{PD}$  is the same range for both measurement and calculation

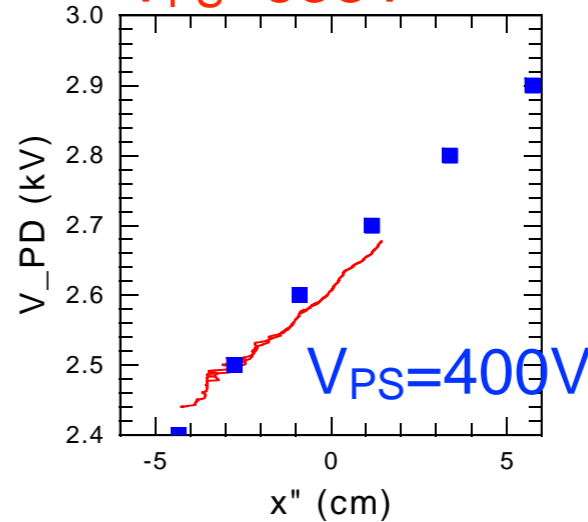
7.69keV

Measurement  
 $V_{PS}=394V$



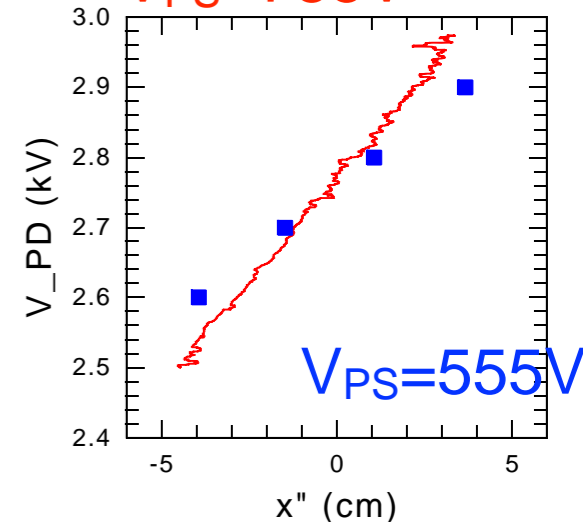
8.64keV

$V_{PS}=638V$



8.64keV

$V_{PS}=785V$



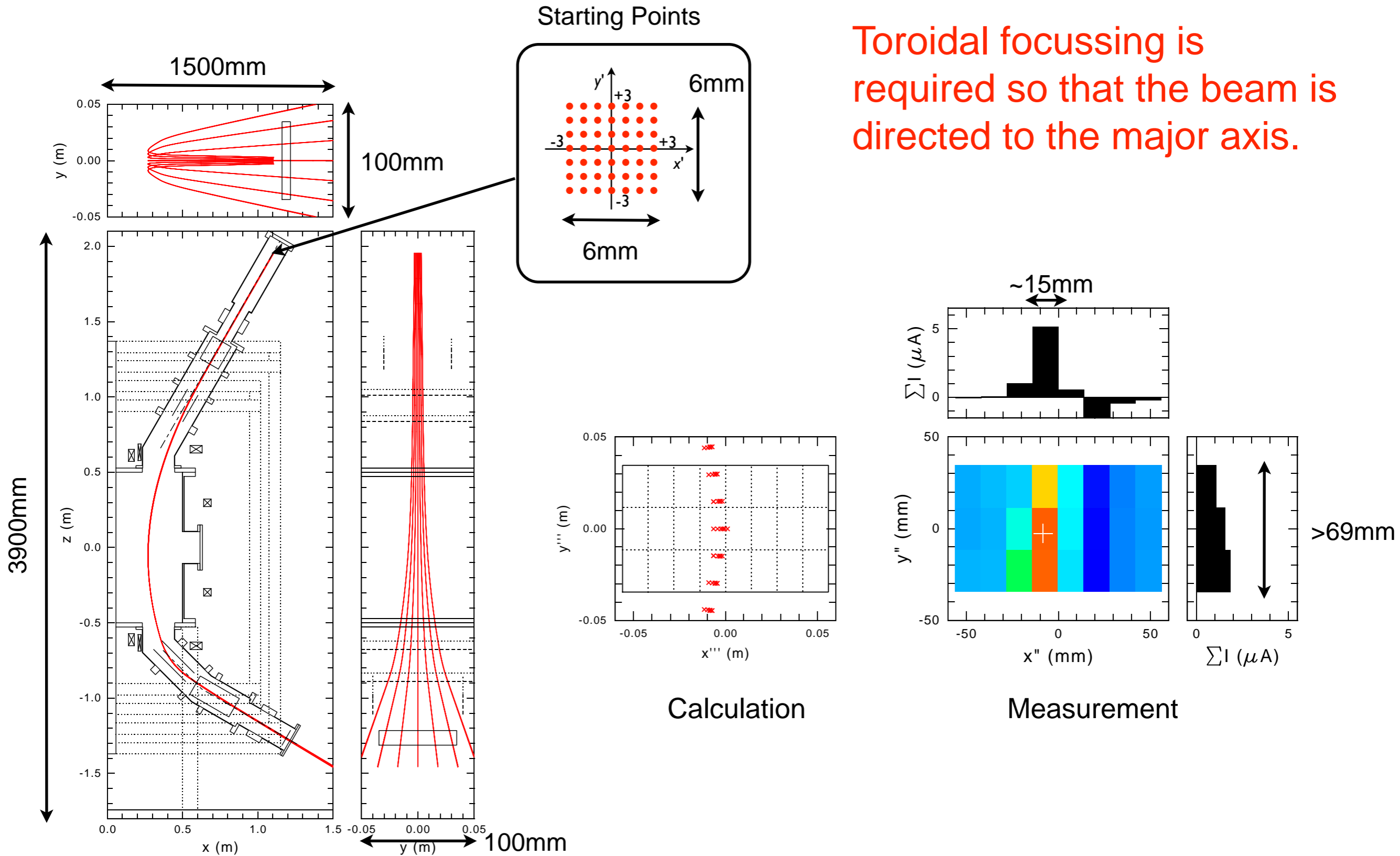
8x3 Matrix Plate Detector





# Beam Spreading in the Toroidal Direction

$V_{GUN}=7.69kV$ ,  $V_{PS}=200V$ ,  $V_{PD}=2200V$

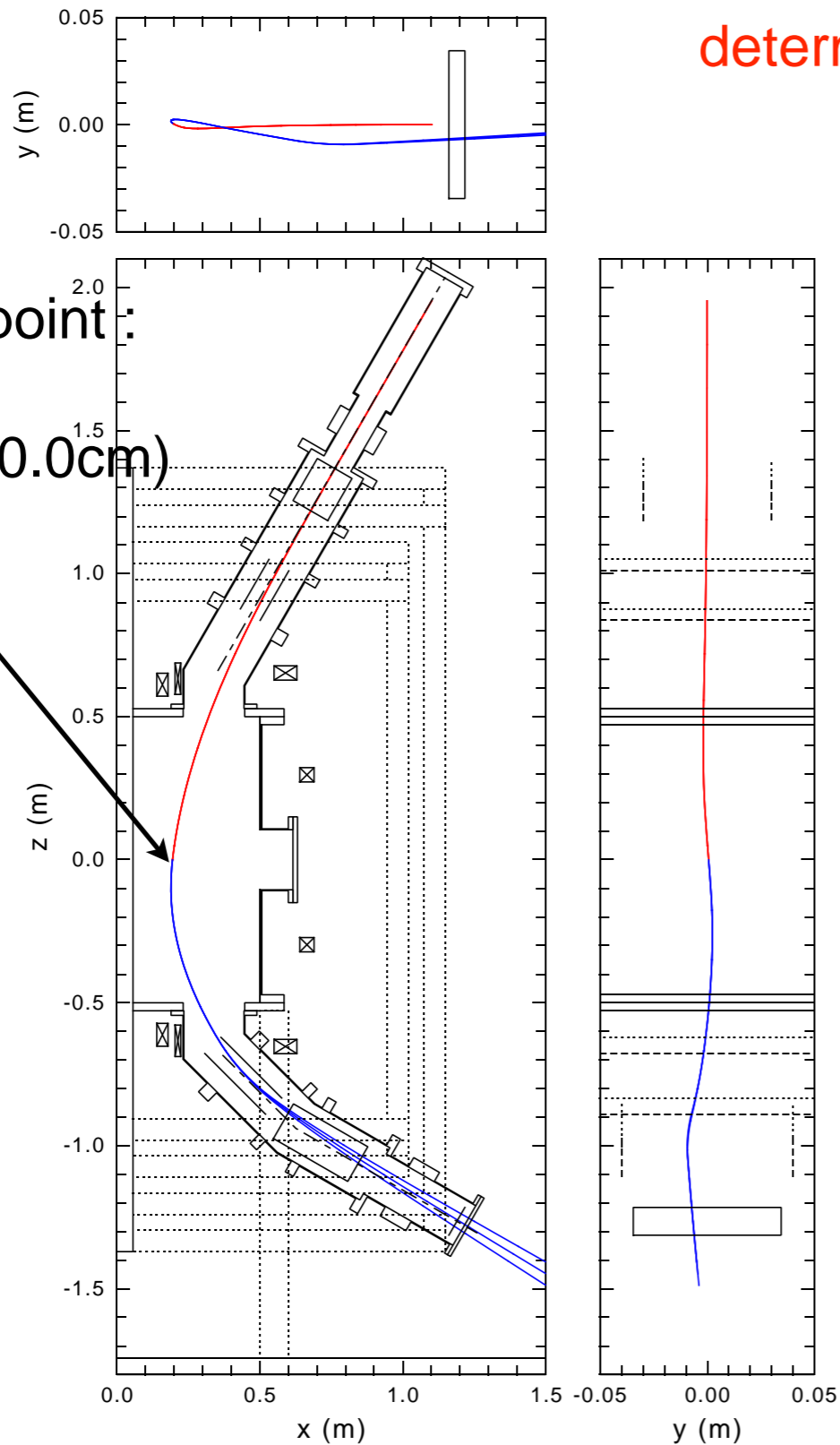


Toroidal focussing is required so that the beam is directed to the major axis.

# Calculation of Secondary Beam Orbit

A set of 5 voltage values ( $V_G$ ,  $V_{PS}$ ,  $V_{TS}$ ,  $V_{PD}$ ,  $V_{TD}$ ) determines an ionization point ( $R_{ion}$ ,  $Z_{ion}$ ).

ionization point:  
 $(R_{ion}, Z_{ion})$   
 $= (19.2\text{cm}, 0.0\text{cm})$



$Rb^+$ ,  $Wk=14\text{keV}$  ( $V_G=14\text{kV}$ )

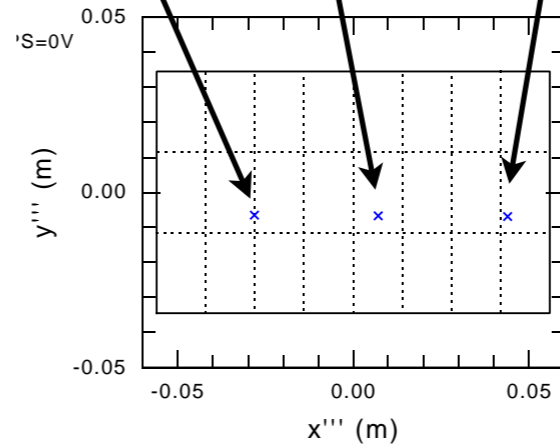
$V_{PS}=0\text{kV}$ ,  $V_{TS}=0\text{kV}$ ,

$V_{TD}=0.1\text{kV}$

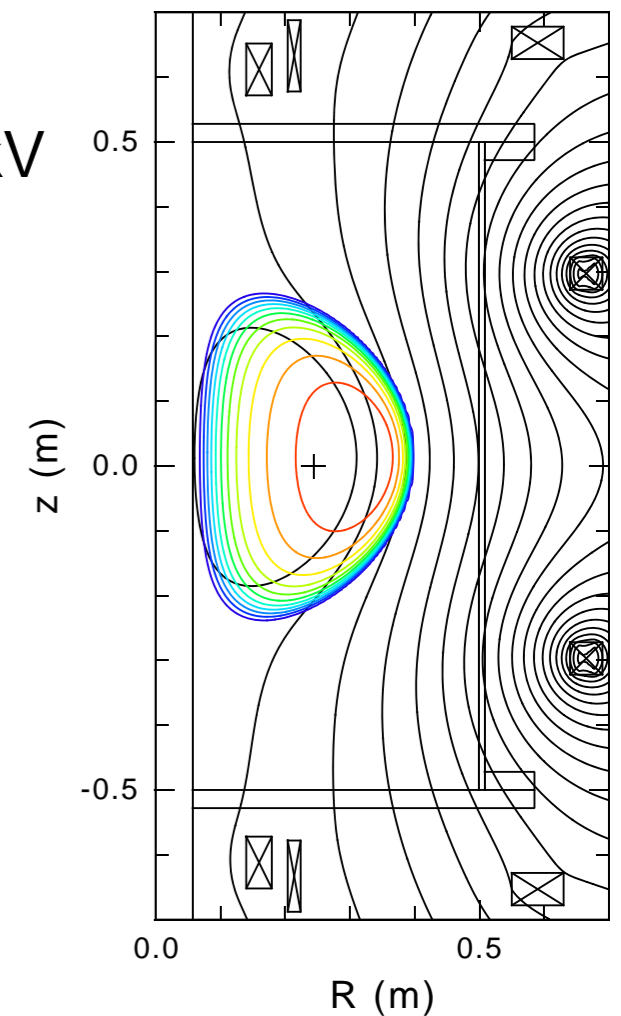
$V_{PD} =$   
**0.8kV**

**0.9kV**

**1.0kV**

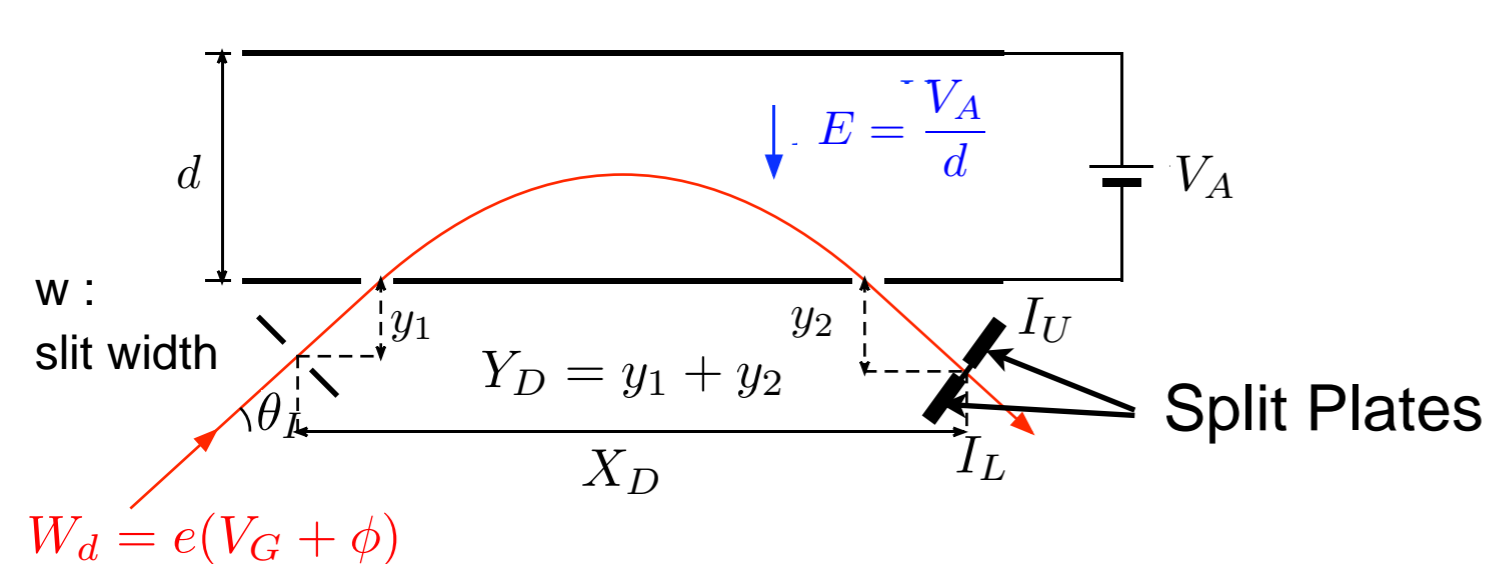


$B_t=720\text{G}$ ,  $I_p=10\text{kA}$



## Green-Proca Type Parallel Plate Energy Analyzer

T.S.Green and G.A.Proca, Rev. Sci. Instrum. 41 (1970) 1409.



$$\theta_I = 30^\circ \quad (\text{Second order focussing})$$

$$\begin{aligned} \frac{W_d}{e} &= V_G + \phi \\ &= V_G + \frac{2w}{\sqrt{3}d} V_A \frac{I_U - I_L}{I_U + I_L} \end{aligned}$$

$$\phi = \frac{2w}{\sqrt{3}d} V_A \frac{I_U - I_L}{I_U + I_L}$$

### Design Parameters

$$\frac{V_G}{V_A} = \frac{4}{3\sqrt{3}} \frac{X_D}{d} = 5 \quad (\text{Gain Parameter})$$

$$Y_D = \frac{d}{4} \frac{V_G}{V_A}$$

$$X_D = 3\sqrt{3}Y_D$$

w : slit width

## Parameter Comparison

W slit width (mm)	d (mm)	$Y_D$ (mm)	$X_D$ (mm)	Dynamic Range (V) @ $V_G=20kV$	Minimum Detectable Potential Difference * (V)
2	50	62.5	324.8	$\pm 185$	1.85
2	75	93.8	487.1	$\pm 123$	1.23
2	100	125	649.5	$\pm 92$	0.92

\* when  $\frac{\Delta I_{noise}}{I_{total}} = 10^{-2}$

The same parameters used for HIBP in CHS

For Achievement of Minimum Detectable Potential Difference

$$\Delta\phi_m < 1 \text{ V}$$

Current-Voltage Converter (Conventional Type)

Gain :  $4 \times 10^6 \text{ V/A}$

Electrical Noise Level :  $\sim 1 \text{ nA}$

If  $I_{\text{total}} > 100 \text{ nA}$ , then  $\Delta I_{\text{noise}}/I_{\text{total}} < 10^{-2}$

Potential Difference due to the variation of incident angle  $\theta_i$

$$\phi(\Delta\theta_I) = -\frac{40}{\sqrt{3}} V_A (\Delta\theta_I)^3$$

$$\Delta\theta_i < 1.3^\circ \text{ for } \Delta\phi_m < 1 \text{ V}$$

1. We are developing the ion beam probe system for the LATE device to investigate the electric field effect on formation, confinement and transport of the spherical tokamak produced and maintained by EBW/ECW heating and current drive solely.
2. For the plasma parameters on LATE, electron temperature may be estimated as well as potential, magnetic field and their fluctuation measurement.
3. The ion gun, the injection beam line and the collection beam line were installed to LATE and tested. They meet a minimal demand level for the measurement but several developments are still required.
  - Ion source ... increase current up to 100  $\mu\text{A}$
  - Ion gun ... focussing in the toroidal direction
  - Calculation ... improvement of accuracy
4. Initial design of energy analyzer is surveyed for achievement of minimum detectable potential difference less than 1 V.